



**3<sup>rd</sup> MC-PAD Network Training Event,  
Jožef Stefan Institute, Ljubljana, Slovenia**

*- 29 September 2010 -*

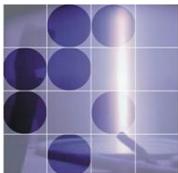


# **Radiation Hardness of Semiconductor Detectors**

*- Radiation Effects and Detector Operation -*

*... including an introduction to ongoing  
radiation tolerant sensors developments*

**Michael Moll (CERN/PH)**



*Michael Moll – MC-PAD Network Training,  
Ljubljana, 27.9.2010*



- **Motivation to develop radiation harder detectors**

- LHC upgrade and expected radiation levels
- Radiation induced degradation of detector performance

- **Radiation Damage in Silicon Detectors**

- Microscopic damage (crystal damage), NIEL
- Macroscopic damage (changes in detector properties)

- **Approaches to obtain radiation tolerant sensors**

- **Material Engineering**
  - New silicon materials – FZ, MCZ, DOFZ, EPI
  - Other semiconductors: Diamond, SiC, GaN, ....
- **Device Engineering**
  - p-in-n, n-in-n and n-in-p sensors, 3D sensors and thin devices

- **Silicon Sensors for the LHC upgrade**

..... *open questions and ongoing developments*

- **Summary**

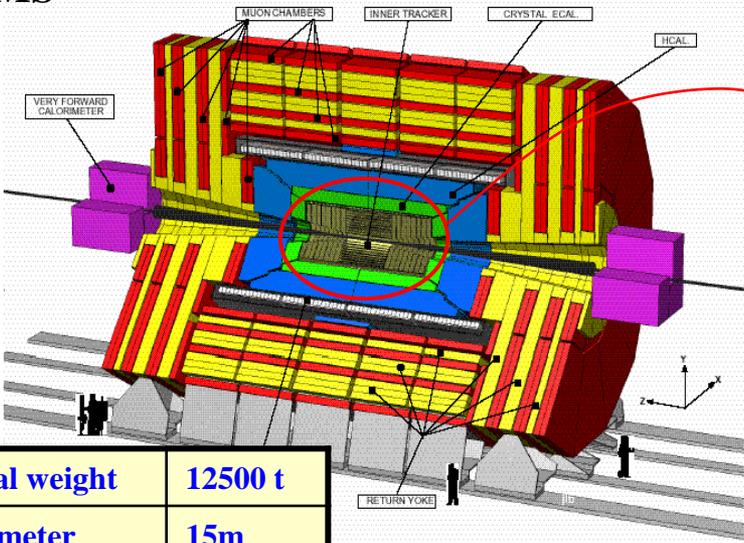
For details on  
**LHC detectors**  
see lecture of  
*Phil Allport*

For details on  
**radiation induced defects**  
see lecture of  
*Ioana Pintilie*

For **surface effects**  
see lecture of  
*G.-F. Dalla Betta*

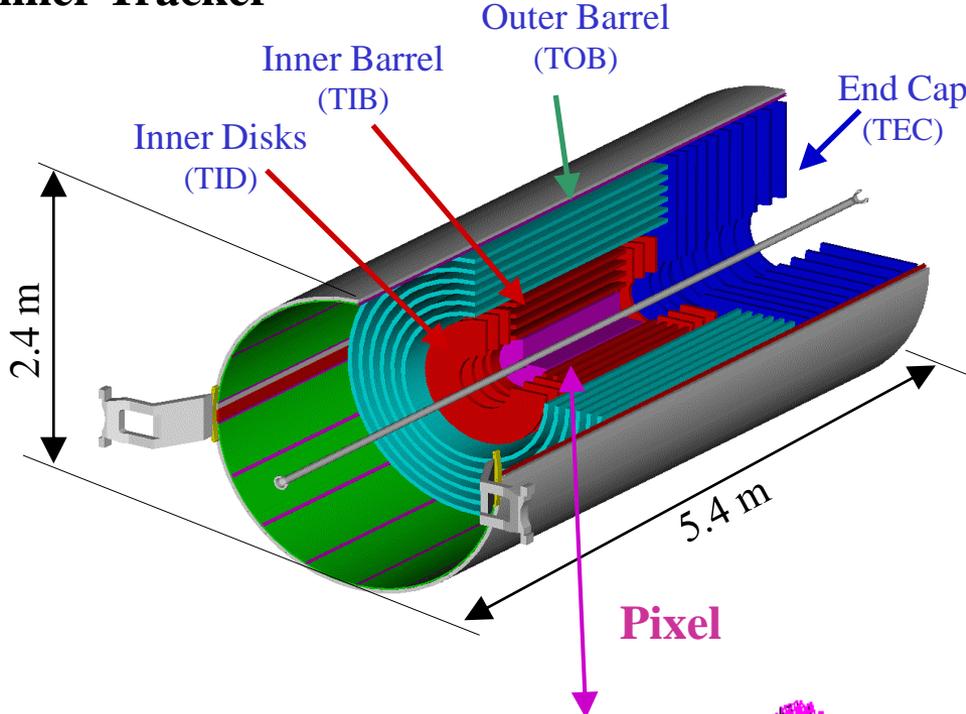
For details on  
**sensor production**  
see lecture of  
*Manolo Lozano*

## CMS



Total weight	12500 t
Diameter	15m
Length	21.6m
Magnetic field	4 T

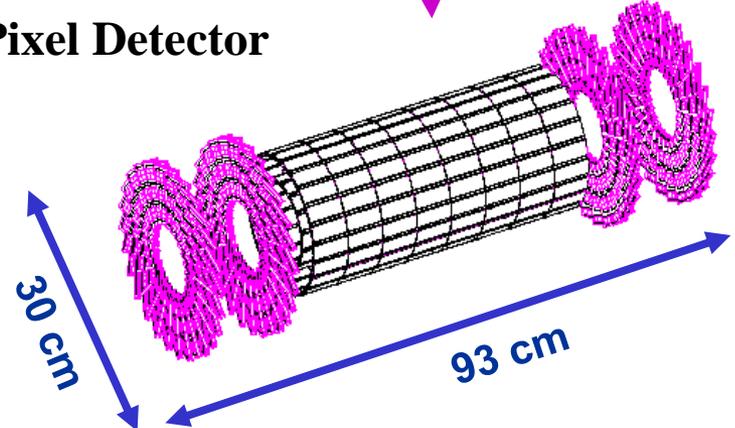
## Inner Tracker



## CMS – “Currently the Most Silicon”

- **Micro Strip:**
- ~ 214 m<sup>2</sup> of silicon strip sensors, 11.4 million strips
- **Pixel:**
- Inner 3 layers: silicon pixels (~ 1m<sup>2</sup>)
- 66 million pixels (100x150µm)
- Precision:  $\sigma(r\phi) \sim \sigma(z) \sim 15\mu\text{m}$
- Most challenging operating environments (LHC)

## Pixel Detector





# Radiation levels after 3000 fb<sup>-1</sup>

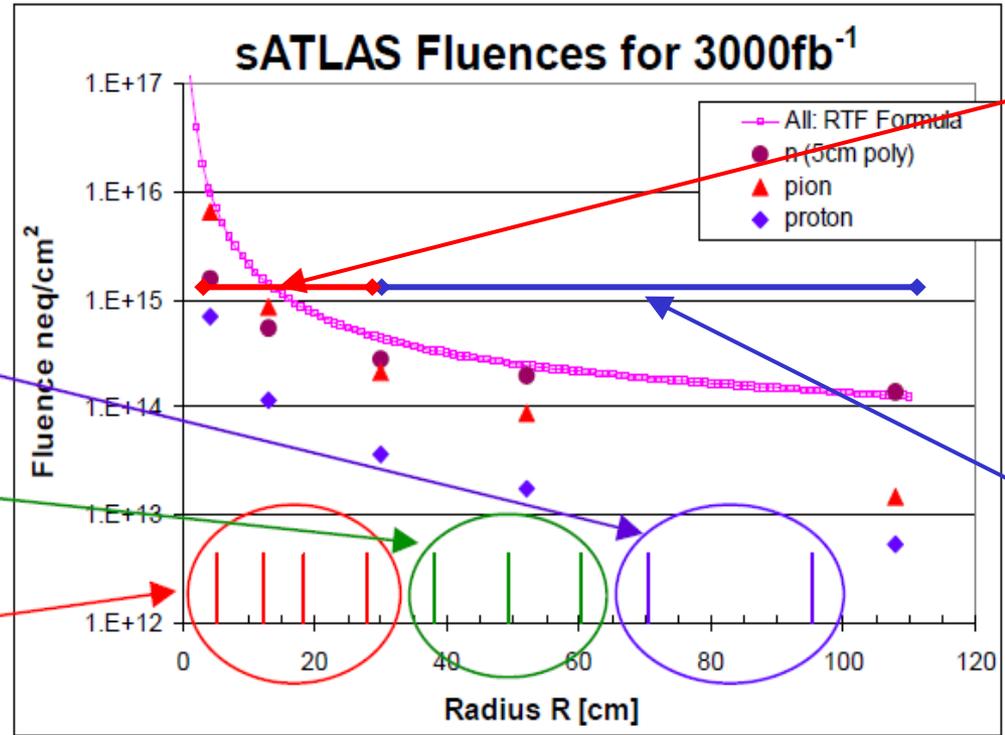


Radial distribution of sensors determined by Occupancy

Long Strips  
(up to  $4 \times 10^{14} \text{ cm}^{-2}$ )

Short Strips  
(up to  $10^{15} \text{ cm}^{-2}$ )

Pixels  
(up to  $10^{16} \text{ cm}^{-2}$ )



ATLAS Radiation Taskforce [ATL-GEN-2005-01] & H.Sadrozinski [IEEE NSS 2007]

## • Radiation hardness requirements (including safety factor of 2)

- $2 \times 10^{16} \text{ n}_{\text{eq}}/\text{cm}^2$  for the innermost pixel layers
- $7 \times 10^{14} \text{ n}_{\text{eq}}/\text{cm}^2$  for the innermost strip layers

B-layer (R=3.7 cm):	$2.5 \times 10^{16} \text{ n}_{\text{eq}}/\text{cm}^2 = 1140 \text{ Mrad}$
2 <sup>nd</sup> Inner Pixel Layer (R=7 cm):	$7.8 \times 10^{15} \text{ n}_{\text{eq}}/\text{cm}^2 = 420 \text{ Mrad}$
1 <sup>st</sup> Outer Pixel Layer (R=11 cm):	$3.6 \times 10^{15} \text{ n}_{\text{eq}}/\text{cm}^2 = 207 \text{ Mrad}$
Short strips (R=38 cm):	$6.8 \times 10^{14} \text{ n}_{\text{eq}}/\text{cm}^2 = 30 \text{ Mrad}$
Long strips (R=85 cm):	$3.2 \times 10^{14} \text{ n}_{\text{eq}}/\text{cm}^2 = 8.4 \text{ Mrad}$

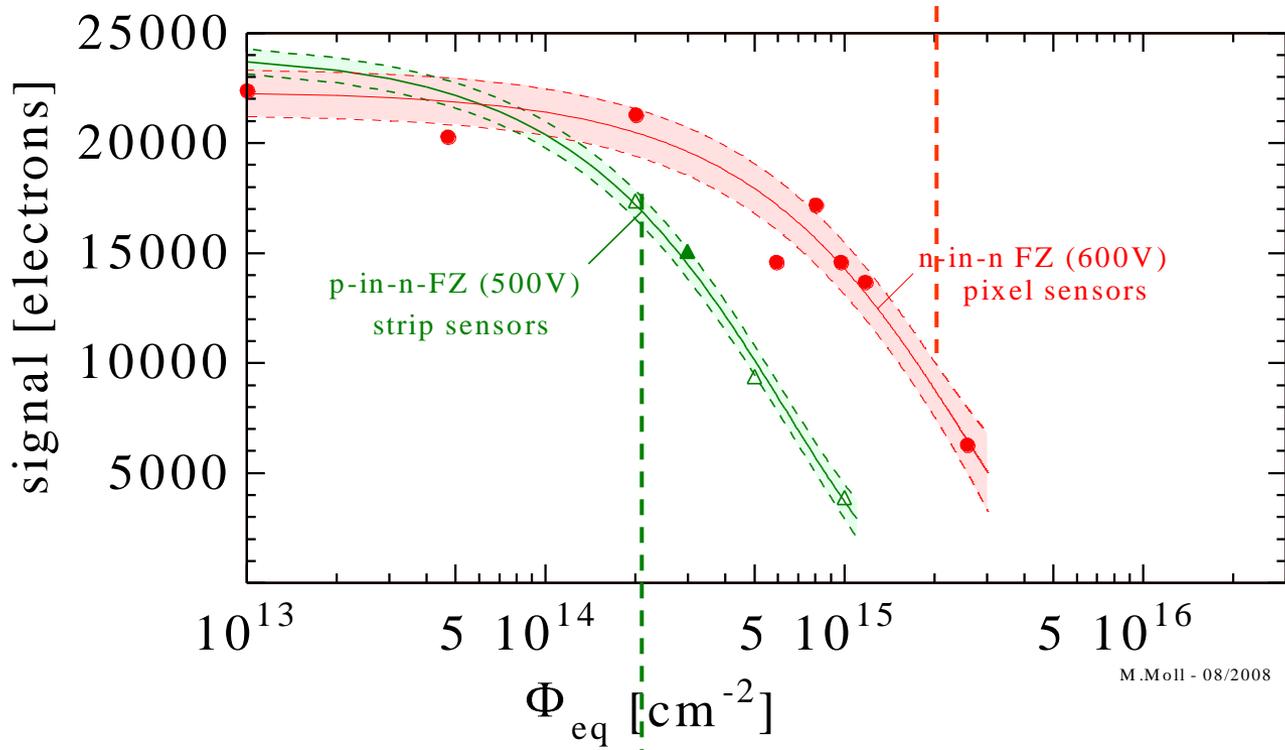


# Signal degradation for LHC Silicon Sensors



**Pixel sensors:**  
**max. cumulated fluence for LHC**

**Note:** Measured partly under different conditions!  
Lines to guide the eye (no modeling)!



FZ Silicon  
Strip and Pixel Sensors

- n-in-n (FZ), 285μm, 600V, 23 GeV p
- ▲ p-in-n (FZ), 300μm, 500V, 23GeV p
- △ p-in-n (FZ), 300μm, 500V, neutrons

References:

- [1] p/n-FZ, 300μm, (-30°C, 25ns), strip [Casse 2008]
- [2] n/n-FZ, 285μm, (-10°C, 40ns), pixel [Rohe et al. 2005]

M.Moll - 08/2008

**Strip sensors:**  
**max. cumulated fluence for LHC**

**Situation in 2005**

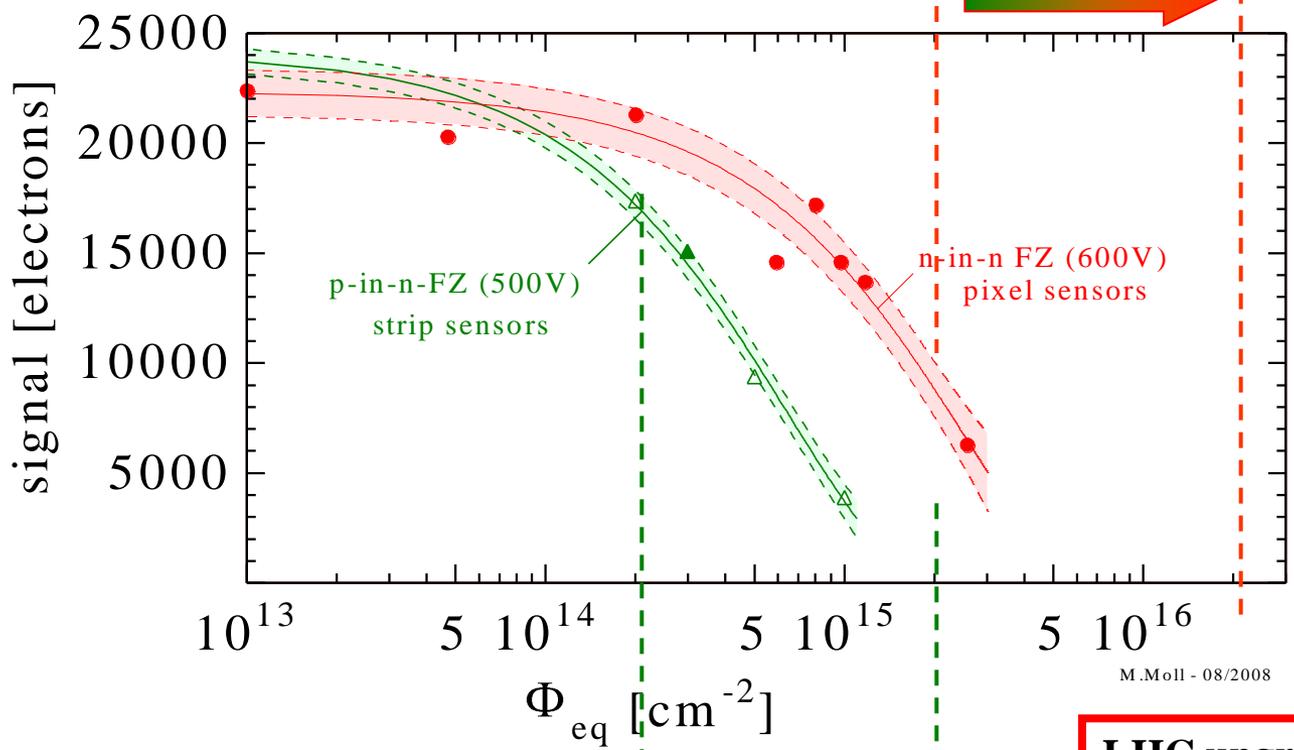


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**Pixel sensors:**  
max. cumulated fluence for **LHC** and **LHC upgrade**



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Strip and Pixel Sensors

- n-in-n (FZ), 285 $\mu$ m, 600V, 23 GeV p
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M.Moll - 08/2008

**Strip sensors:**  
max. cumulated fluence for **LHC** and **LHC upgrade**

**LHC upgrade will need more radiation tolerant tracking detector concepts!**

*Boundary conditions & other challenges:  
Granularity, Powering, Cooling, Connectivity,  
Triggering, Low mass, Low cost!*



# Outline

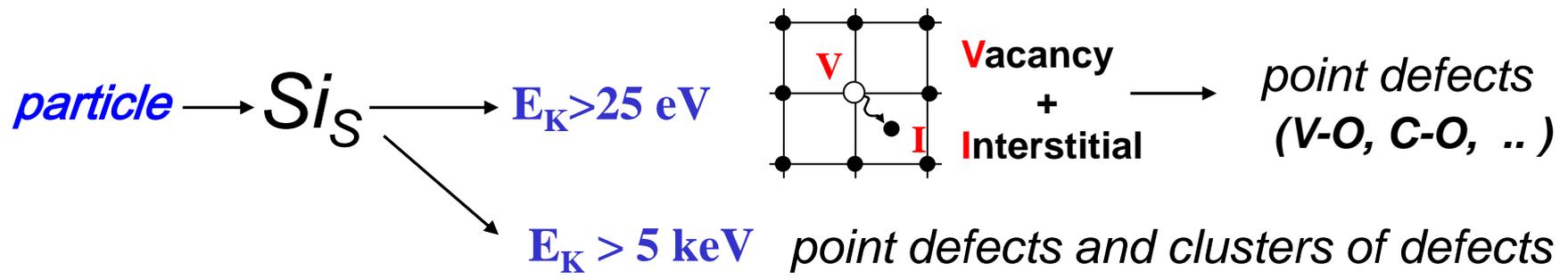
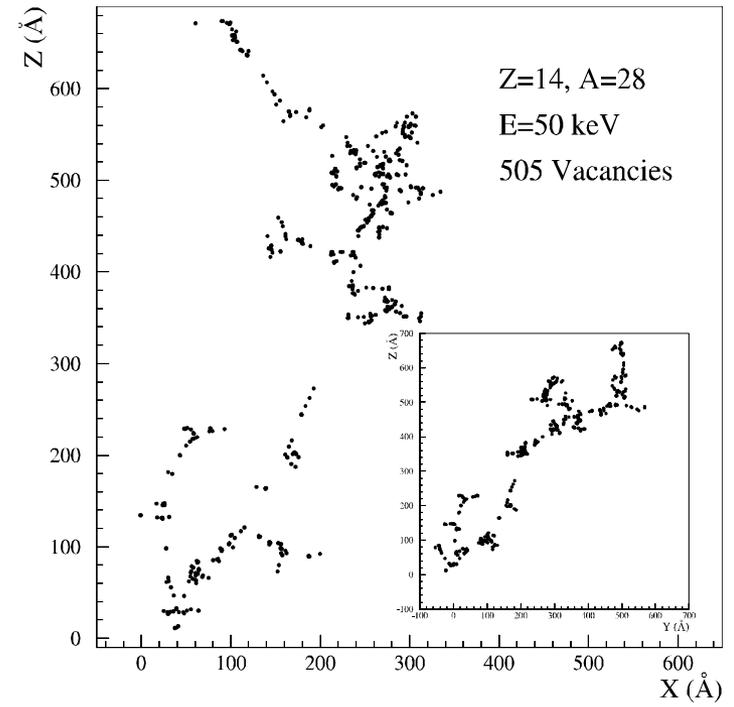
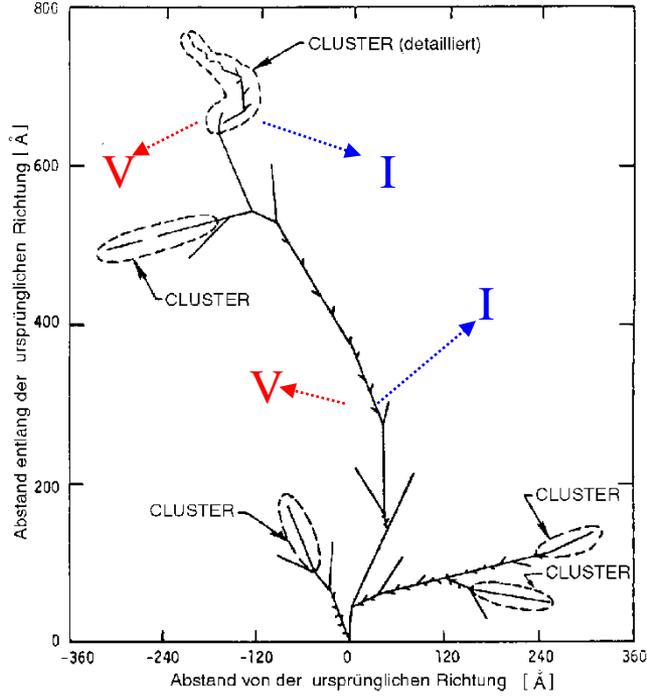


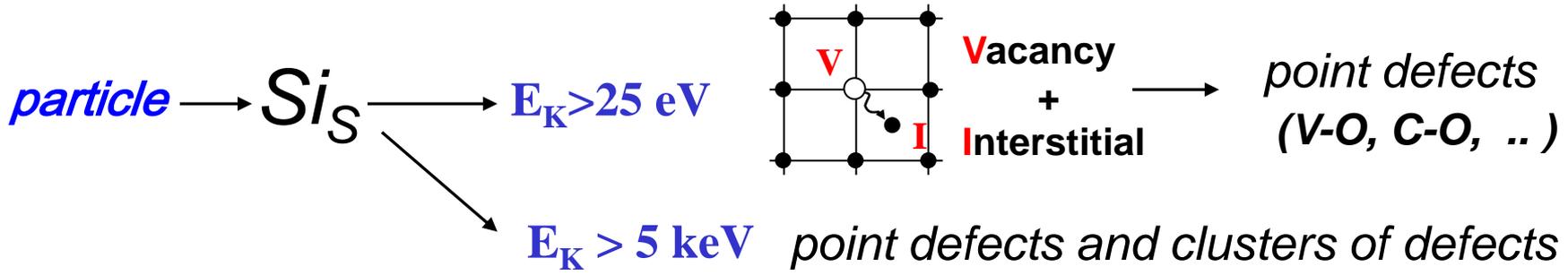
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*..... open questions and ongoing developments*
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- ◆ **Spatial distribution of vacancies created by a 50 keV Si-ion in silicon.**  
(typical recoil energy for 1 MeV neutrons)

M.Huhtinen 2001

van Lint 1980





•  **$^{60}\text{Co}$ -gammas**

- Compton Electrons with max.  $E_\gamma \approx 1 \text{ MeV}$  (no cluster production)

• **Electrons**

- $E_e > 255 \text{ keV}$  for displacement
- $E_e > 8 \text{ MeV}$  for cluster

• **Neutrons (elastic scattering)**

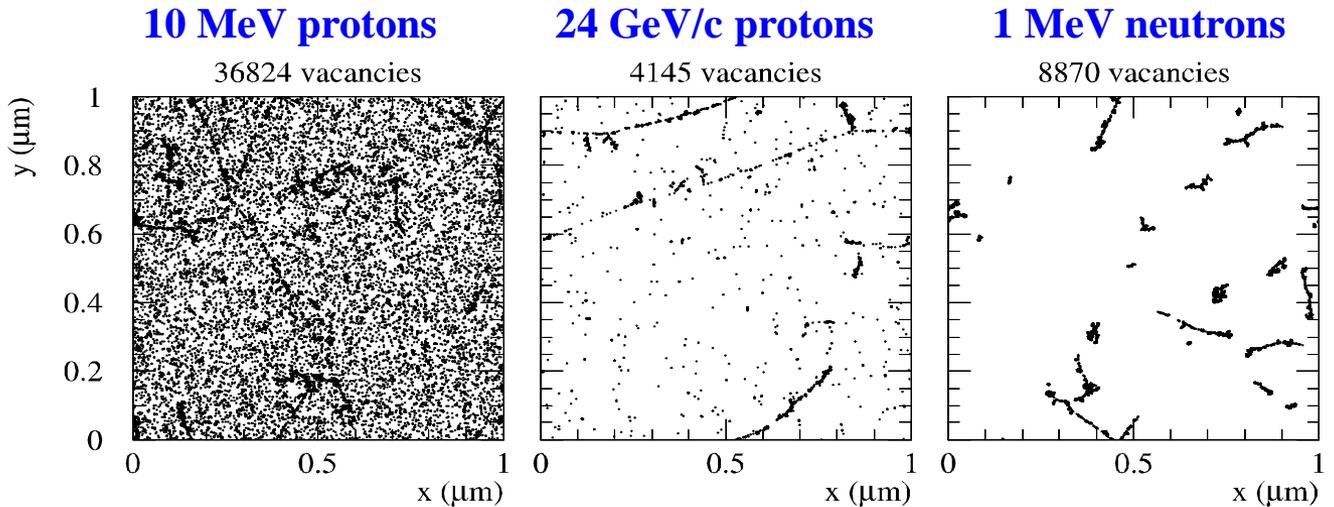
- $E_n > 185 \text{ eV}$  for displacement
- $E_n > 35 \text{ keV}$  for cluster

**Only point defects**  $\longleftrightarrow$  **point defects & clusters**  $\longleftrightarrow$  **Mainly clusters**

**Simulation:**

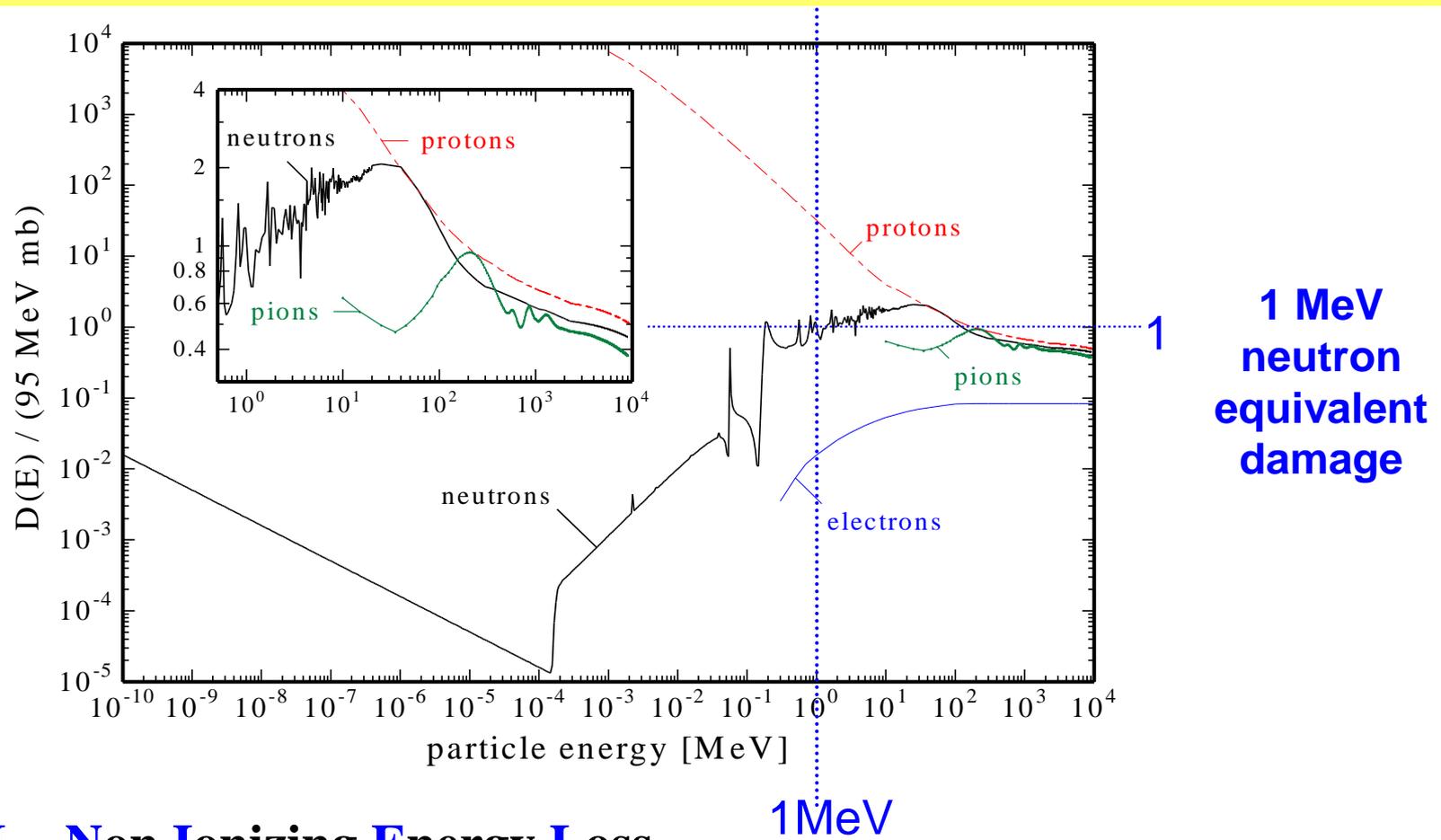
**Initial distribution of vacancies in  $(1\mu\text{m})^3$  after  $10^{14}$  particles/cm $^2$**

[Mika Huhtinen NIMA 491(2002) 194]





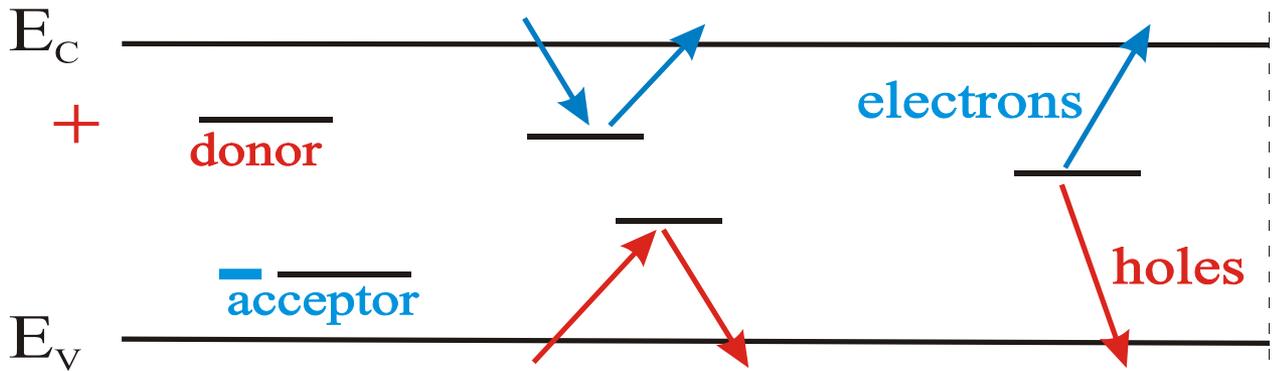
# NIEL - Displacement damage functions



- **NIEL - Non Ionizing Energy Loss**
- **NIEL - Hypothesis: Damage parameters scale with the NIEL**
  - *Be careful, does not hold for all particles & damage parameters (see later)*

Details in next lecture by Ioana Pintilie on defects.

## Shockley-Read-Hall statistics



**charged defects**  
 $\Rightarrow N_{\text{eff}}, V_{\text{dep}}$   
 e.g. donors in upper and acceptors in lower half of band gap

**Trapping (e and h)**  
 $\Rightarrow \text{CCE}$   
 shallow defects do not contribute at room temperature due to fast detrapping

**generation**  
 $\Rightarrow$  leakage current  
 Levels close to midgap most effective

**Impact on detector properties can be calculated if all defect parameters are known:**

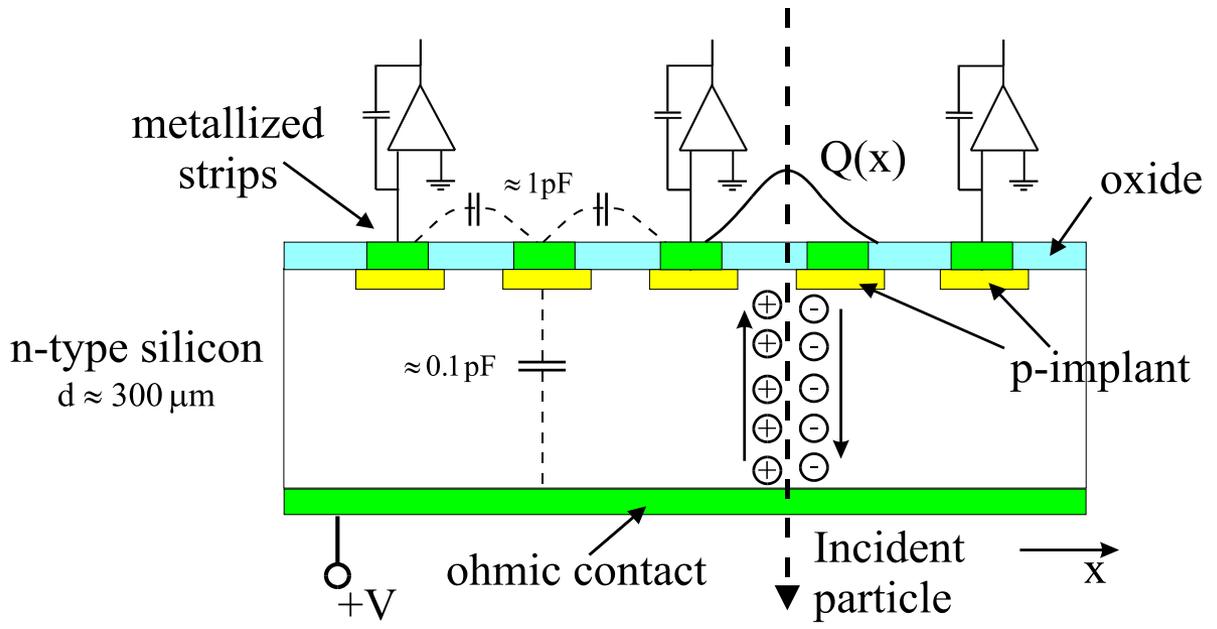
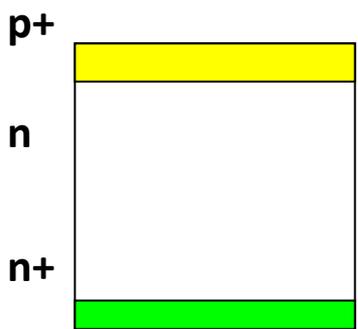
$\sigma_{n,p}$  : cross sections

$\Delta E$  : ionization energy

$N_t$  : concentration

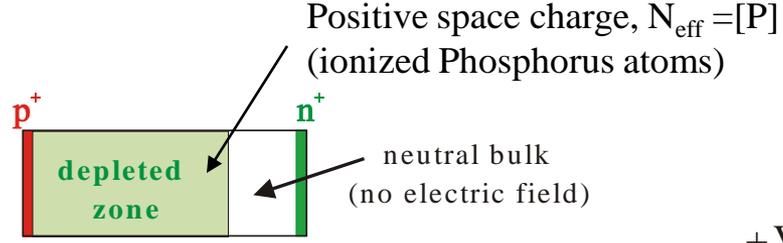
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- **Summary**

- Detectors are basically **p<sup>+</sup>- n diodes made on high resistivity silicon**
- **Standard detector grade silicon:**
  - Float Zone silicon (FZ)
  - n-type: 2...20 KΩcm
  - [P] = 20...2×10<sup>11</sup> cm<sup>-3</sup> (very low concentration !! below 1ppba = 5×10<sup>13</sup>cm<sup>-3</sup>)
  - [O] ≈ several 10<sup>15</sup>cm<sup>-3</sup>
  - [C] ≈ some 10<sup>15</sup>cm<sup>-3</sup>, usually [C] < [O]
  - crystal orientation: <111> or <100>

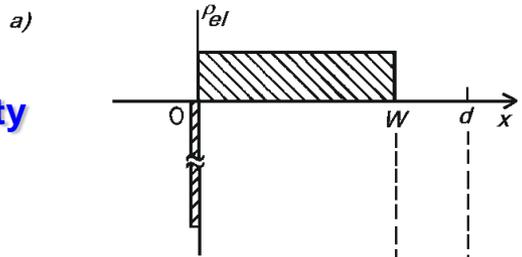


Poisson's equation

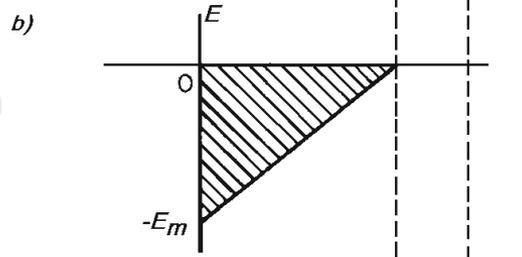
$$-\frac{d^2 \phi}{dx^2} = \frac{q_0}{\epsilon \epsilon_0} \cdot N_{eff}$$



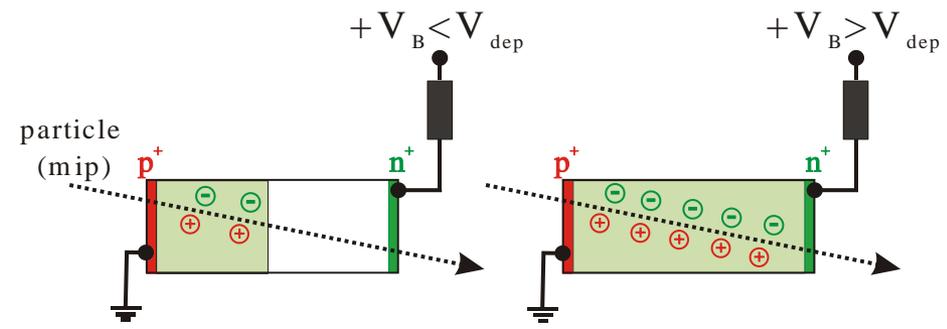
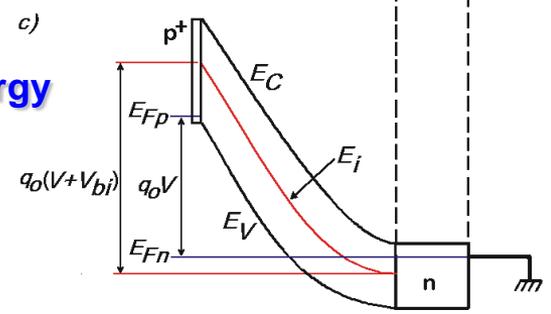
Electrical charge density



Electrical field strength



Electron potential energy



Full charge collection only for  $V_B > V_{dep}$  !

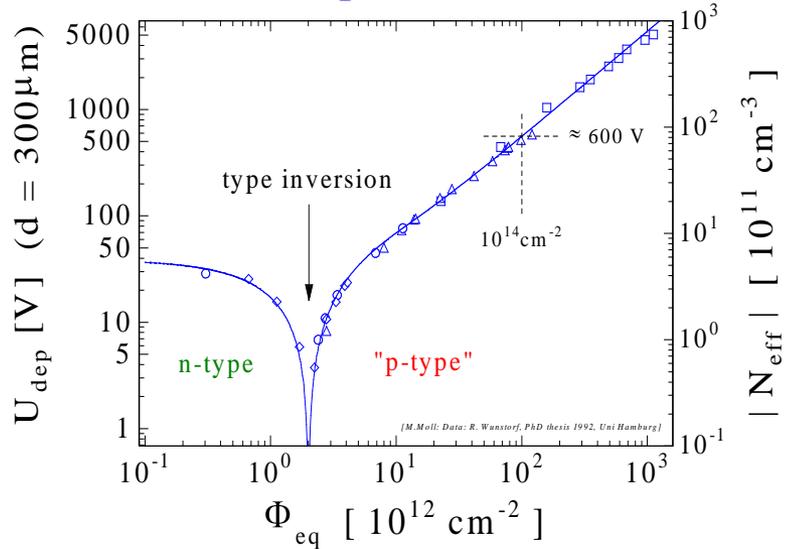
depletion voltage

$$V_{dep} = \frac{q_0}{\epsilon \epsilon_0} \cdot |N_{eff}| \cdot d^2$$

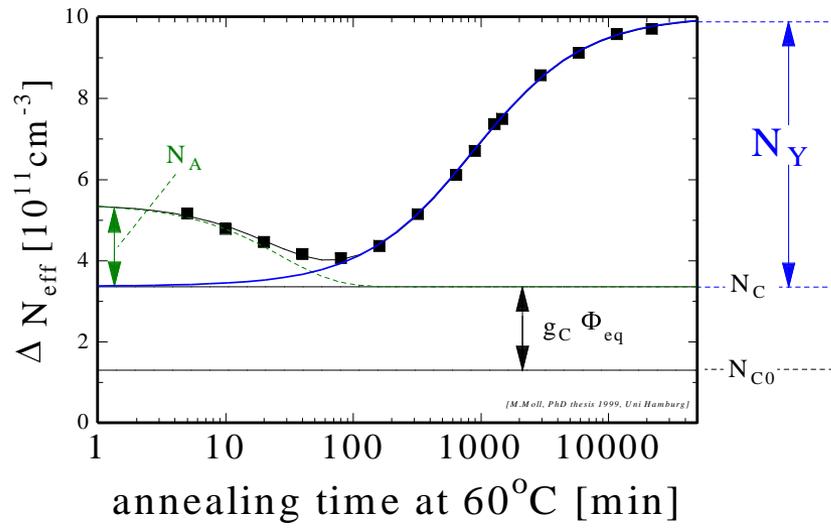
effective space charge density

## Change of Depletion Voltage $V_{dep}$ ( $N_{eff}$ )

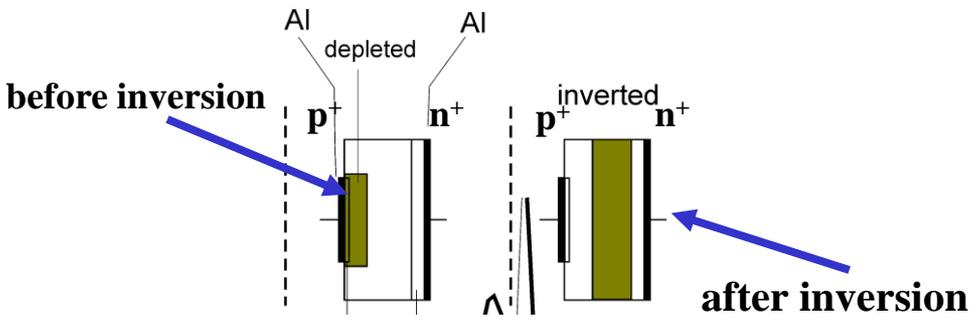
.... with particle fluence:



.... with time (annealing):



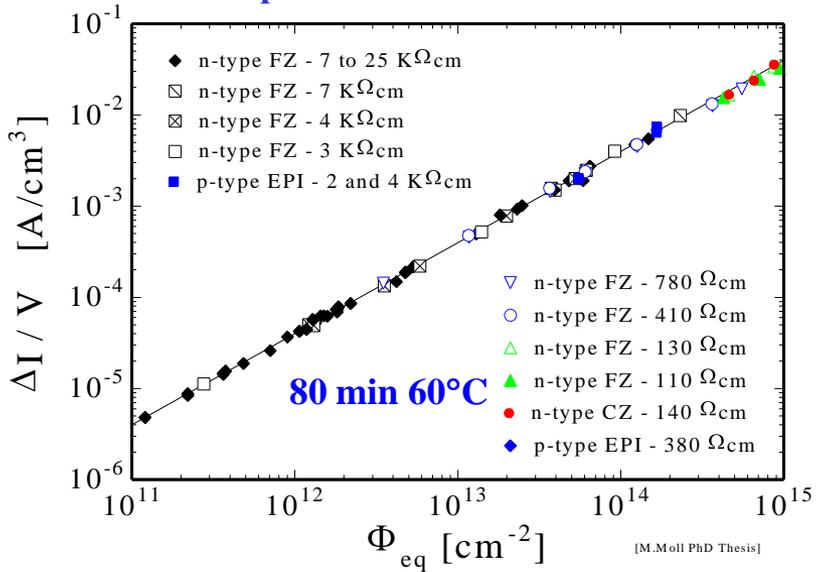
• “**Type inversion**”:  $N_{eff}$  changes from positive to negative (Space Charge Sign Inversion)



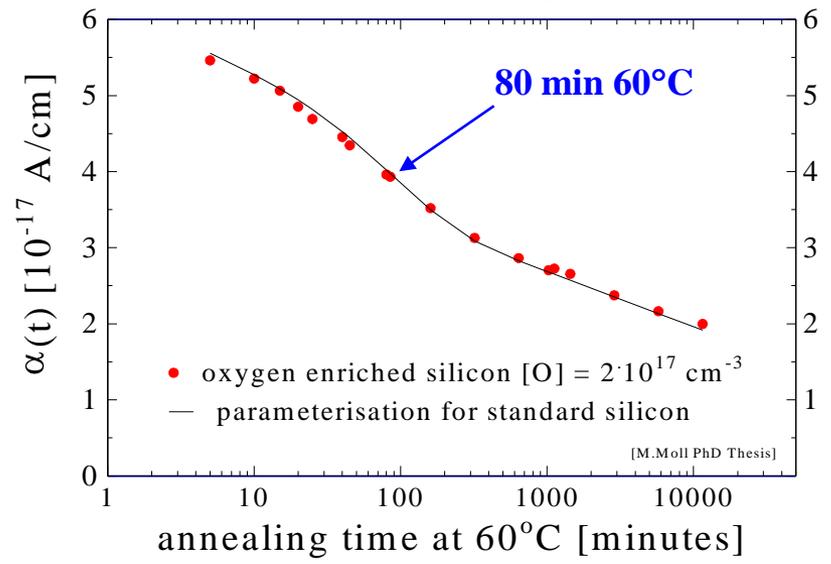
- Short term: “**Beneficial annealing**”
- Long term: “**Reverse annealing**”
- time constant depends on temperature:
  - ~ 500 years (-10 C)
  - ~ 500 days (20 C)
  - ~ 21 hours (60 C)
- Consequence: **Detectors must be cooled even when the experiment is not running!**

## Change of Leakage Current (after hadron irradiation)

.... with particle fluence:



.... with time (annealing):



- Damage parameter  $\alpha$  (slope in figure)

$$\alpha = \frac{\Delta I}{V \cdot \Phi_{eq}}$$

Leakage current per unit volume and particle fluence

- $\alpha$  is constant over several orders of fluence and independent of impurity concentration in Si  
 ⇒ can be used for fluence measurement

- Leakage current decreasing in time (depending on temperature)
- Strong temperature dependence

$$I \propto \exp\left(-\frac{E_g}{2k_B T}\right)$$

Consequence:

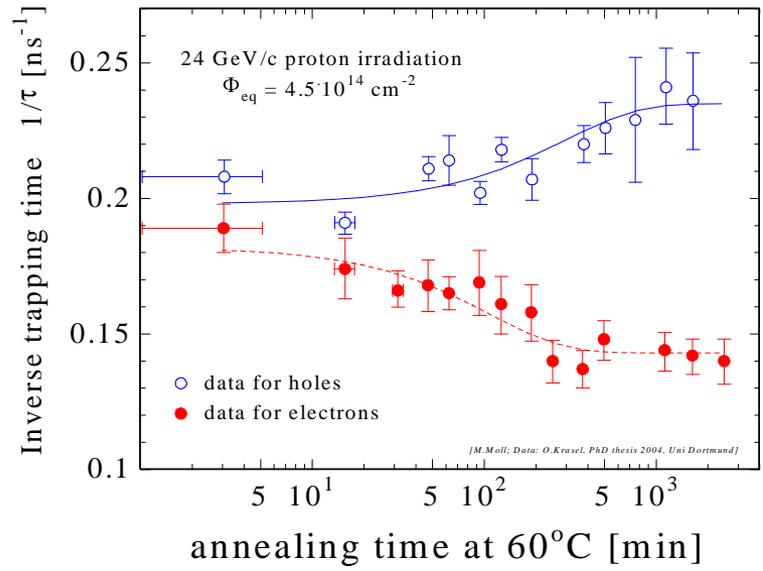
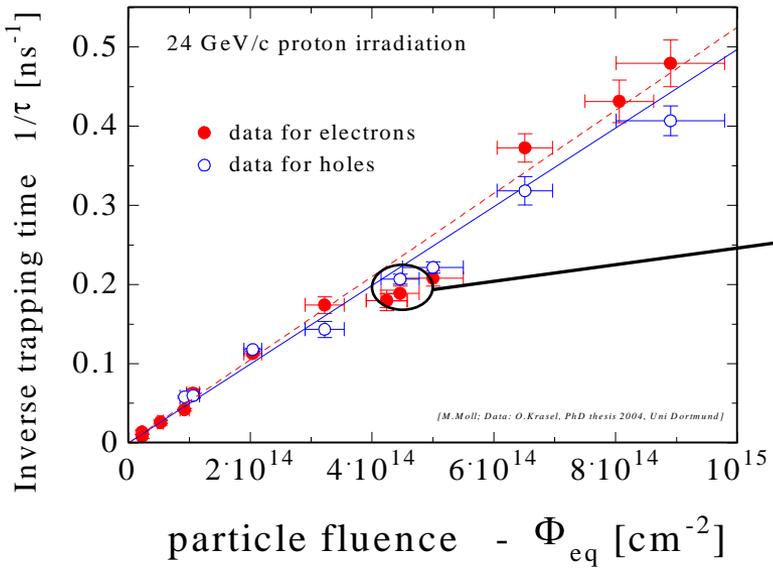
Cool detectors during operation!  
 Example:  $I(-10\text{ C}) \sim 1/16 I(20\text{ C})$

## ■ Deterioration of Charge Collection Efficiency (CCE) by trapping

**Trapping** is characterized by an effective trapping time  $\tau_{eff}$  for electrons and holes:

$$Q_{e,h}(t) = Q_{0e,h} \exp\left(-\frac{1}{\tau_{eff\ e,h}} \cdot t\right) \quad \text{where} \quad \frac{1}{\tau_{eff\ e,h}} \propto N_{defects}$$

Increase of inverse trapping time ( $1/\tau$ ) with fluence ..... and change with time (annealing):





# Summary: Radiation Damage in Silicon Sensors



## ■ Two general types of radiation damage to the detector materials:

### ● Bulk (Crystal) damage due to Non Ionizing Energy Loss (NIEL)

- displacement damage, built up of crystal defects –

Influenced by impurities in Si – Defect Engineering is possible!

I. Change of **effective doping concentration** (higher depletion voltage, under- depletion)

II. Increase of **leakage current** (increase of shot noise, thermal runaway)

III. Increase of **charge carrier trapping** (loss of charge)

Same for all tested Silicon materials!

### ● Surface damage due to Ionizing Energy Loss (IEL)

- accumulation of positive in the oxide ( $\text{SiO}_2$ ) and the Si/ $\text{SiO}_2$  interface – affects: interstrip capacitance (noise factor), breakdown behavior, ...

## ■ Impact on detector performance and Charge Collection Efficiency

(depending on detector type and geometry and readout electronics!)

Signal/noise ratio is the quantity to watch

⇒ Sensors can fail from radiation damage !

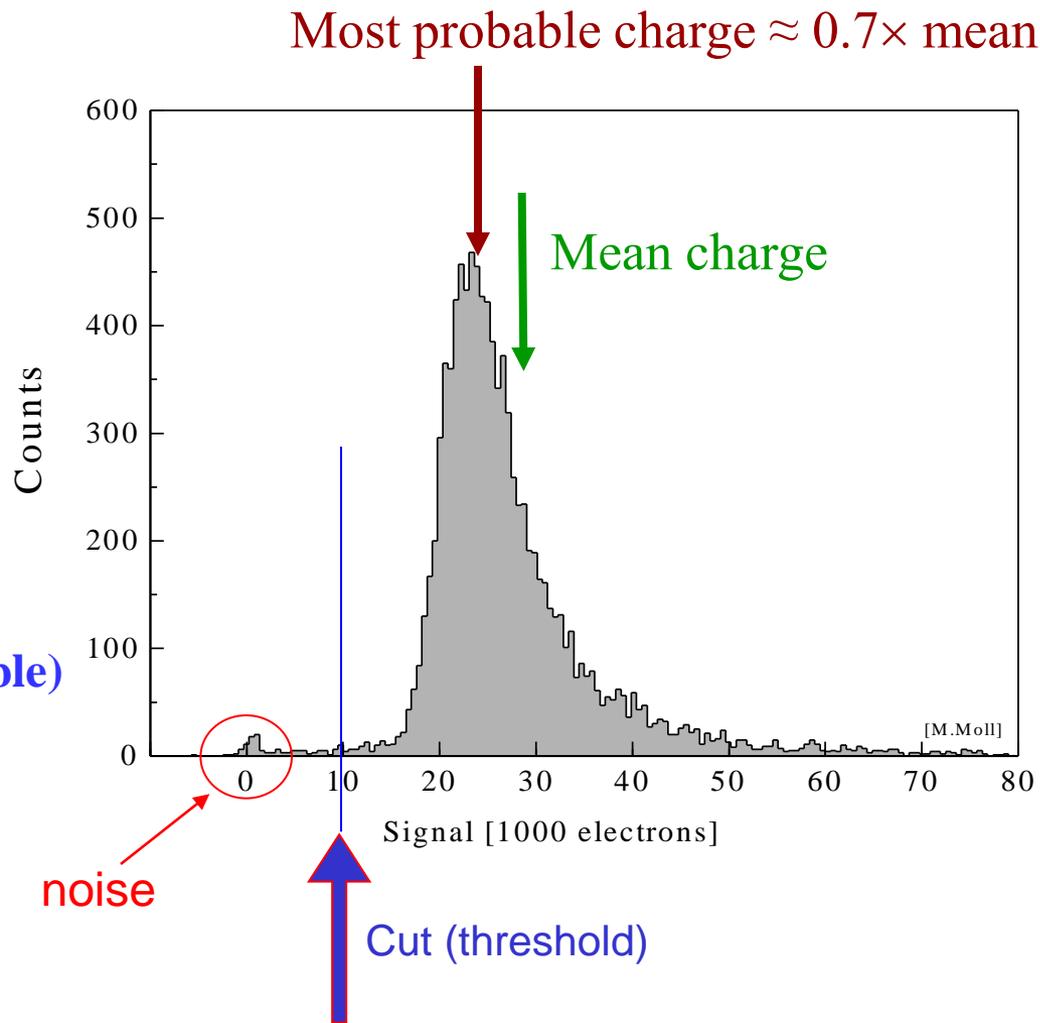
Can be optimized!

## ■ Collected Charge for a Minimum Ionizing Particle (MIP)

- Mean energy loss  
 $dE/dx$  (Si) = 3.88 MeV/cm  
⇒ 116 keV for 300 $\mu$ m thickness
- Most probable energy loss  
 $\approx 0.7 \times$  mean  
⇒ 81 keV
- 3.6 eV to create an e-h pair  
⇒ 72 e-h /  $\mu$ m (mean)  
⇒ 108 e-h /  $\mu$ m (most probable)

- Most probable charge (300  $\mu$ m)

$\approx 22500$  e       $\approx 3.6$  fC



- Landau distribution has a low energy tail
  - becomes even lower by noise broadening
- Noise sources: (ENC = Equivalent Noise Charge)

- Capacitance  $ENC \propto C_d$

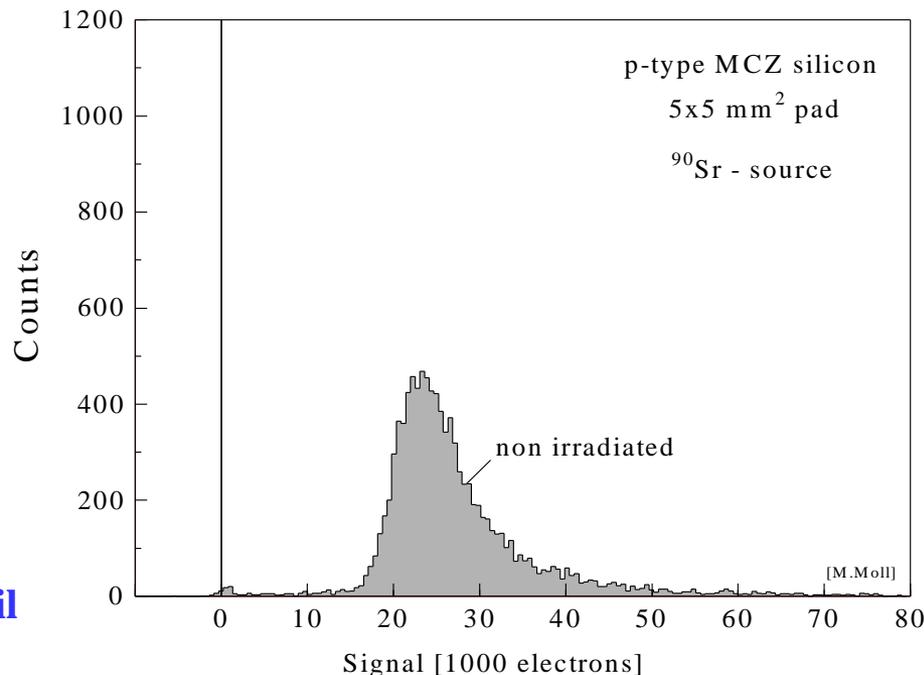
- Leakage Current  $ENC \propto \sqrt{I}$

- Thermal Noise (bias resistor)  $ENC \propto \sqrt{\frac{k_B T}{R}}$

- Good hits selected by requiring NADC > noise tail
  - If cut too high  $\Rightarrow$  efficiency loss
  - If cut too low  $\Rightarrow$  noise occupancy

■ Figure of Merit: Signal-to-Noise Ratio S/N

■ Typical values >10-15, people get nervous below 10.  
Radiation damage severely degrades the S/N.





# Signal to Noise ratio



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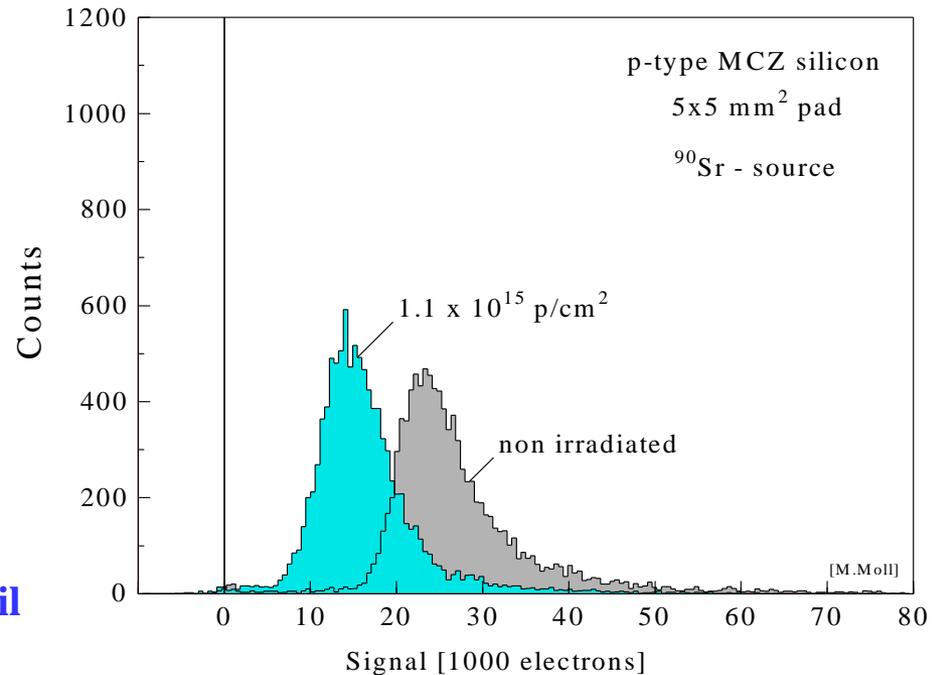
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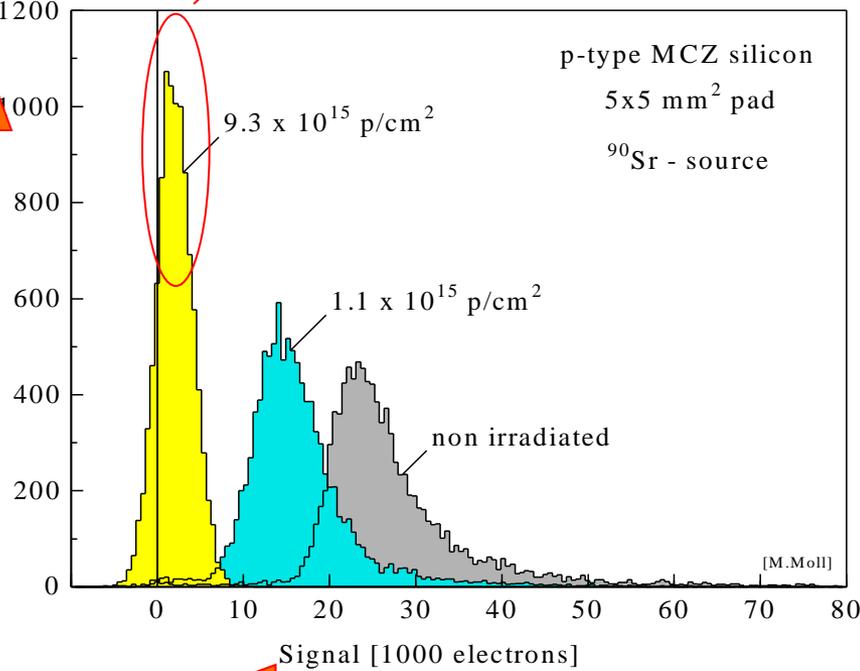
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(bias resistor)

$$ENC \propto \sqrt{\frac{k_B T}{R}}$$

What is signal and what is noise?



more noise



less signal

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If cut too high ⇒ efficiency loss  
If cut too low ⇒ noise occupancy

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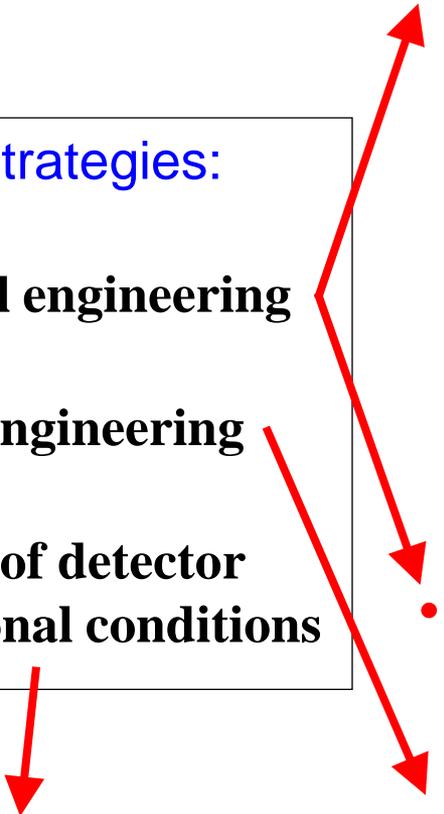


# Approaches to develop radiation harder solid state tracking detectors



Scientific strategies:

- I. Material engineering**
- II. Device engineering**
- III. Change of detector operational conditions**



- **Defect Engineering of Silicon**

*Deliberate incorporation of impurities or defects into the silicon bulk to improve radiation tolerance of detectors*

- **Needs:** Profound understanding of radiation damage
  - microscopic defects, macroscopic parameters
  - dependence on particle type and energy
  - defect formation kinetics and annealing
- **Examples:**
  - **Oxygen rich Silicon** (DOFZ, Cz, MCZ, EPI)
  - Oxygen dimer & hydrogen enriched Si
  - Pre-irradiated Si
  - Influence of processing technology

- **New Materials**

- Silicon Carbide (SiC), Gallium Nitride (GaN)
- Diamond (CERN RD42 Collaboration)
- Amorphous silicon

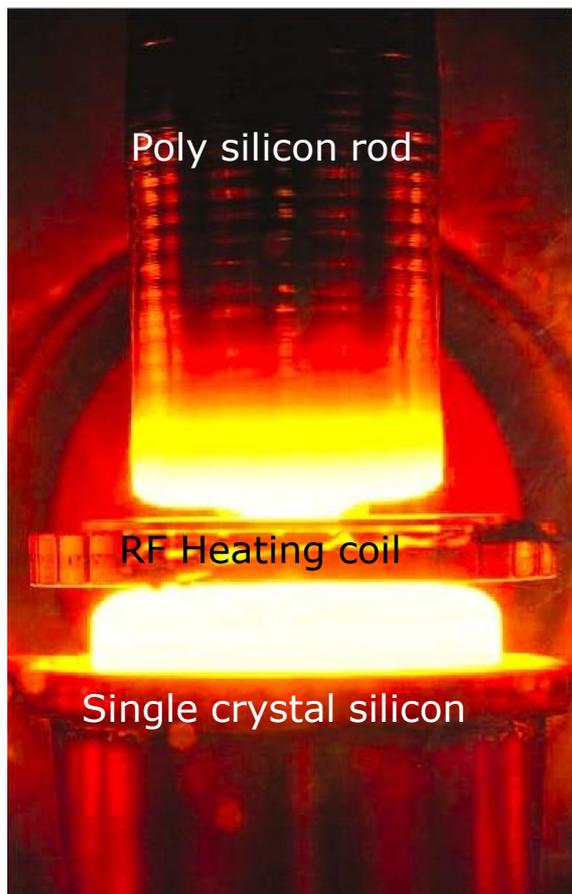
- **Device Engineering (New Detector Designs)**

- **p-type silicon detectors (n-in-p)**
- thin detectors, epitaxial detectors
- **3D detectors** and Semi 3D detectors, Stripixels
- Cost effective detectors
- Monolithic devices

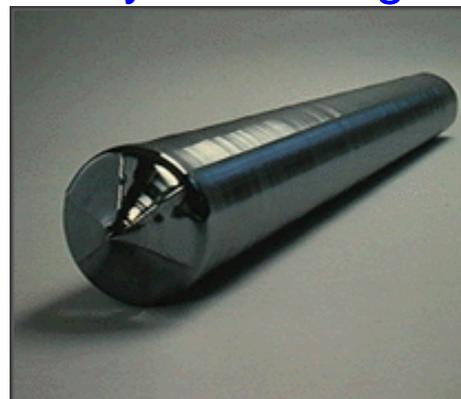
CERN-RD39  
 “Cryogenic Tracking Detectors”  
 operation at 100-200K  
 to reduce charge loss

## ■ Float Zone process

- Using a single Si crystal seed, melt the vertically oriented rod onto the seed using RF power and “pull” the **monocrystalline ingot**



## ■ Mono-crystalline Ingot



## ■ Wafer production

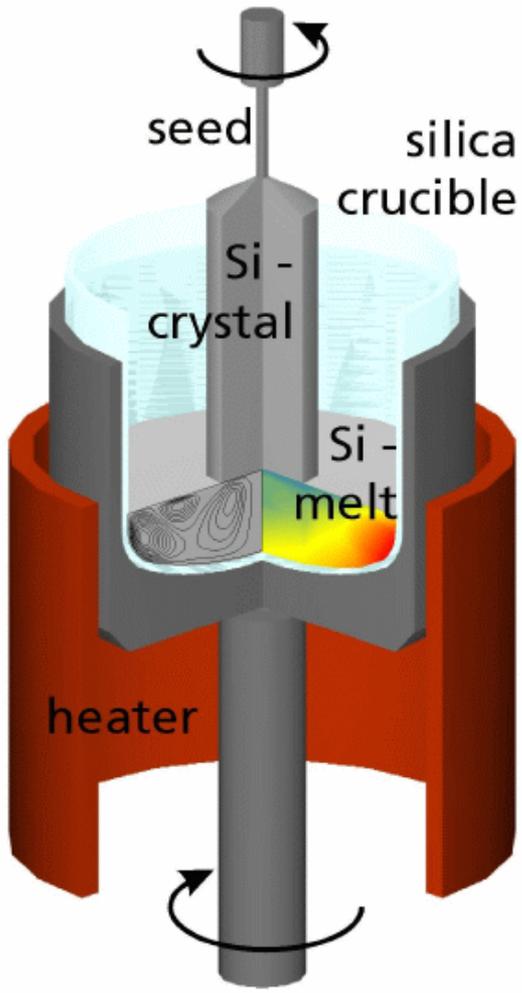
- Slicing, lapping, etching, polishing



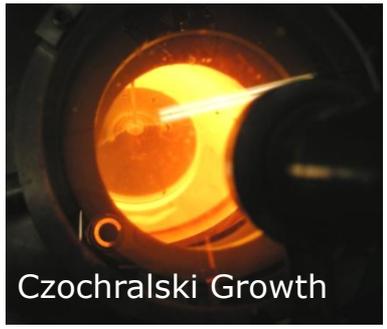
## ■ Oxygen enrichment (DOFZ)

- Oxidation of wafer at high temperatures

## Czochralski silicon



- Pull Si-crystal from a Si-melt contained in a silica crucible while rotating.
- Silica crucible is dissolving oxygen into the melt ⇒ **high concentration of O in CZ**
- Material used by IC industry (cheap)
- Recent developments (~5 years) made CZ available in sufficiently high purity (resistivity) to allow for use as particle detector.

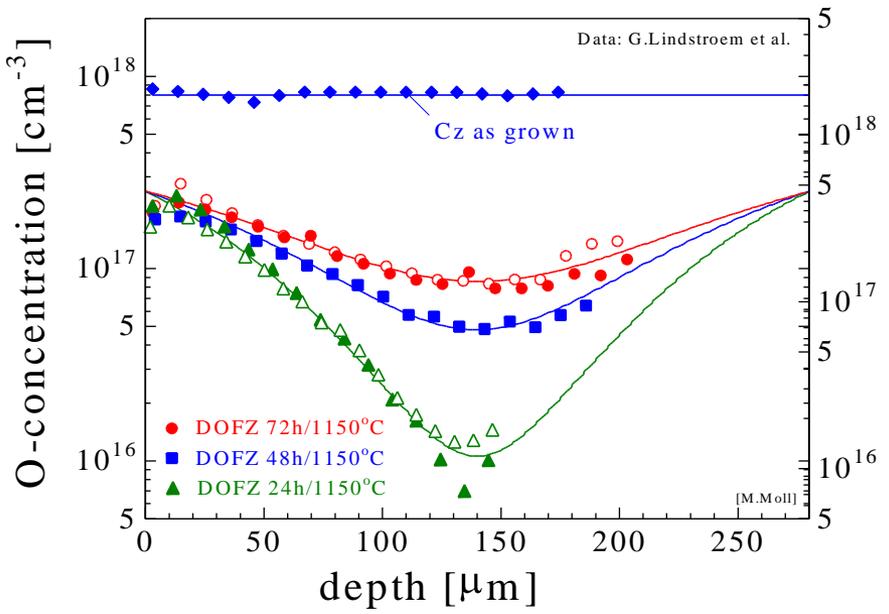


## Epitaxial silicon

- Chemical-Vapor Deposition (CVD) of Silicon
- CZ silicon substrate used ⇒ **in-diffusion of oxygen**
- growth rate about 1µm/min
- excellent homogeneity of resistivity
- up to 150 µm thick layers produced (thicker is possible)
- price depending on thickness of epi-layer but not extending ~ 3 x price of FZ wafer

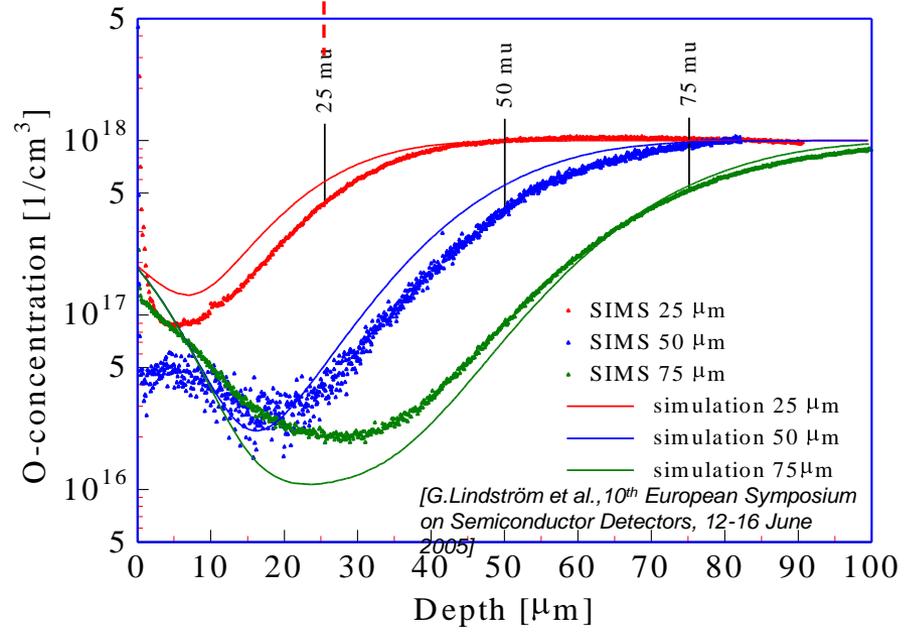
## DOFZ and CZ silicon

- DOFZ: inhomogeneous oxygen distribution
- DOFZ: oxygen content increasing with time at high temperature



- CZ: high  $O_i$  (oxygen) and  $O_{2i}$  (oxygen dimer) concentration (homogeneous)
- CZ: formation of Thermal Donors possible !

## Epitaxial silicon

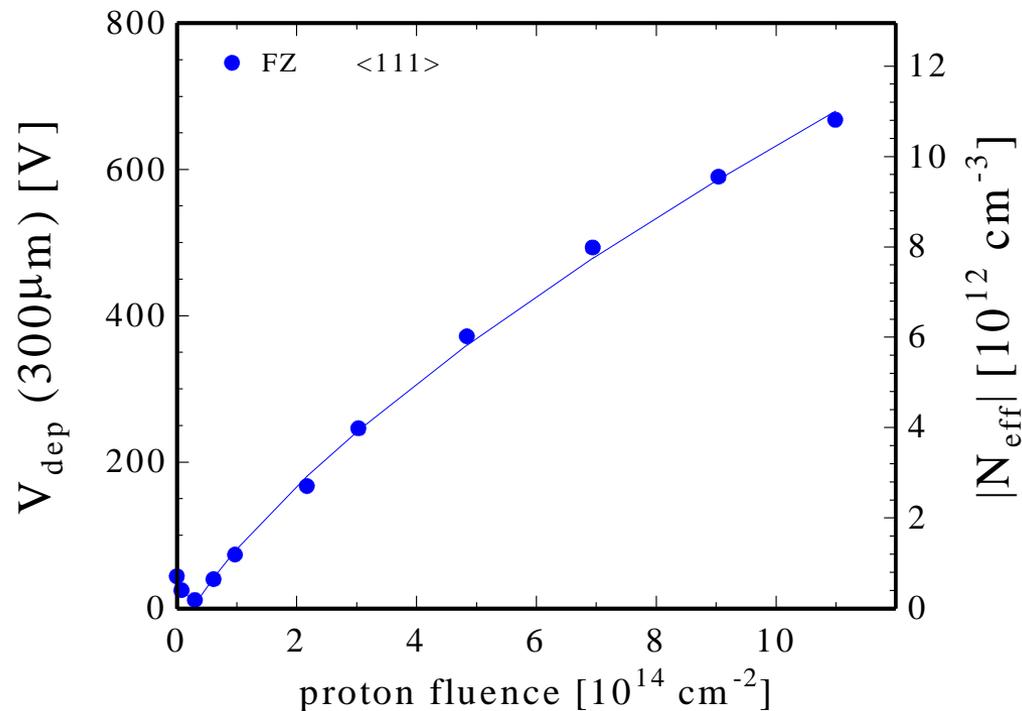


- EPI:  $O_i$  and  $O_{2i}$  (?) diffusion from substrate into epi-layer during production
- EPI: in-homogeneous oxygen distribution

## 24 GeV/c proton irradiation

### • Standard FZ silicon

- type inversion at  $\sim 2 \times 10^{13}$  p/cm<sup>2</sup>
- strong  $N_{\text{eff}}$  increase at high fluence



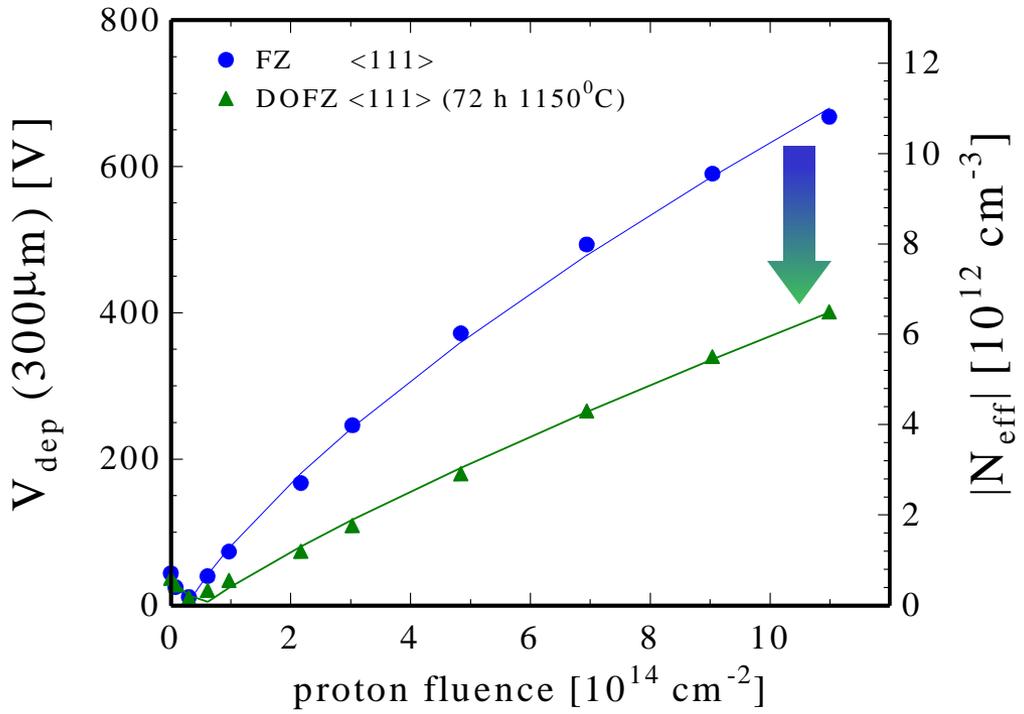
## 24 GeV/c proton irradiation

### • Standard FZ silicon

- type inversion at  $\sim 2 \times 10^{13}$  p/cm<sup>2</sup>
- strong  $N_{\text{eff}}$  increase at high fluence

### • Oxygenated FZ (DOFZ)

- type inversion at  $\sim 2 \times 10^{13}$  p/cm<sup>2</sup>
- reduced  $N_{\text{eff}}$  increase at high fluence



## 24 GeV/c proton irradiation

### • Standard FZ silicon

- type inversion at  $\sim 2 \times 10^{13}$  p/cm<sup>2</sup>
- strong  $N_{\text{eff}}$  increase at high fluence

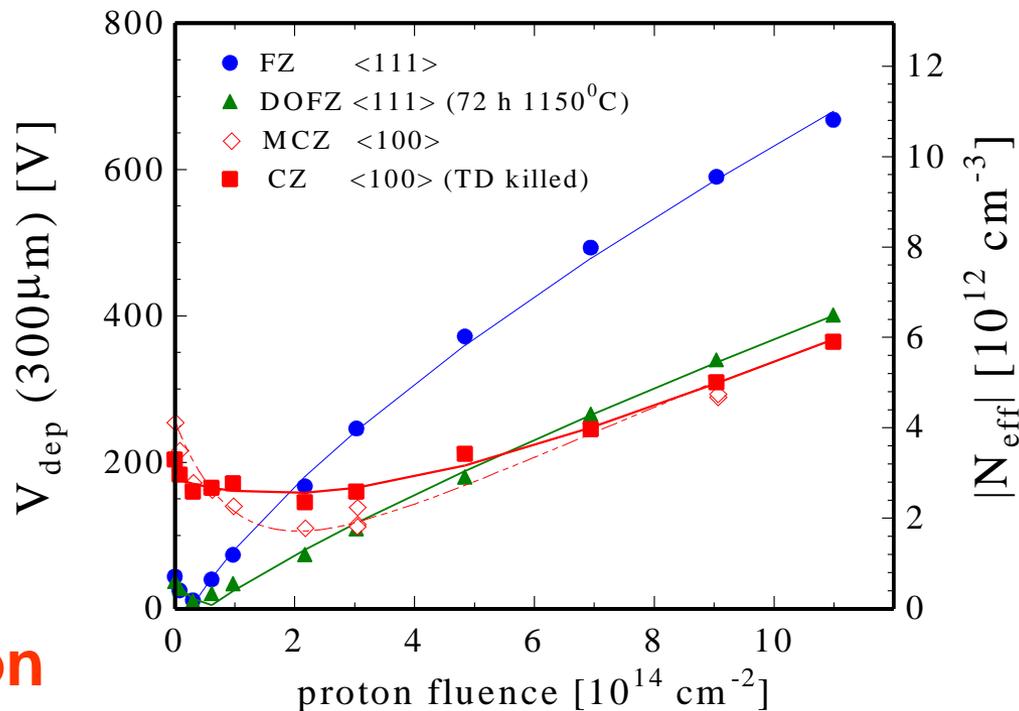
### • Oxygenated FZ (DOFZ)

- type inversion at  $\sim 2 \times 10^{13}$  p/cm<sup>2</sup>
- reduced  $N_{\text{eff}}$  increase at high fluence

### • CZ silicon and MCZ silicon

- “no type inversion” in the overall fluence range

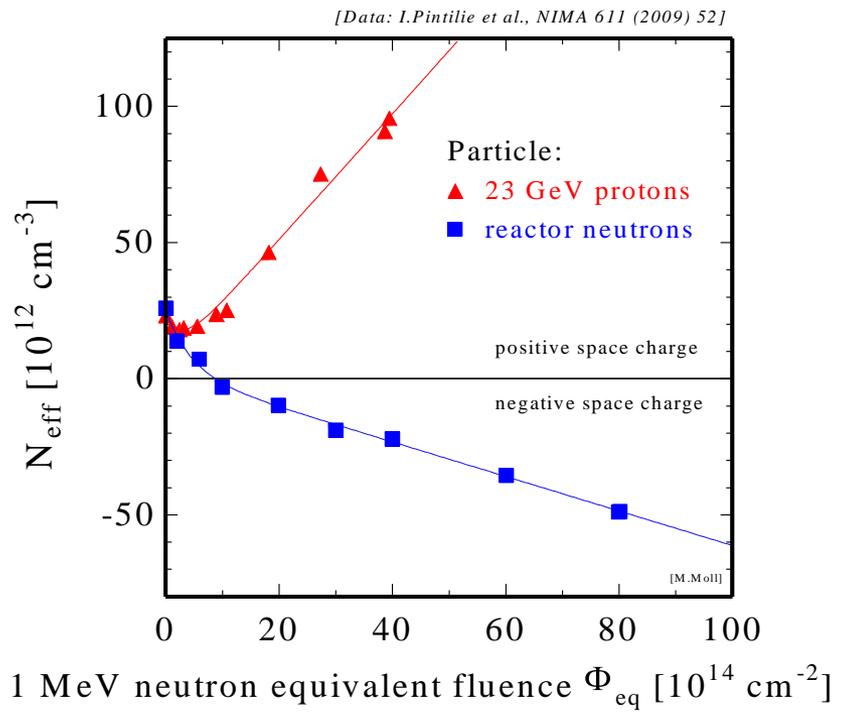
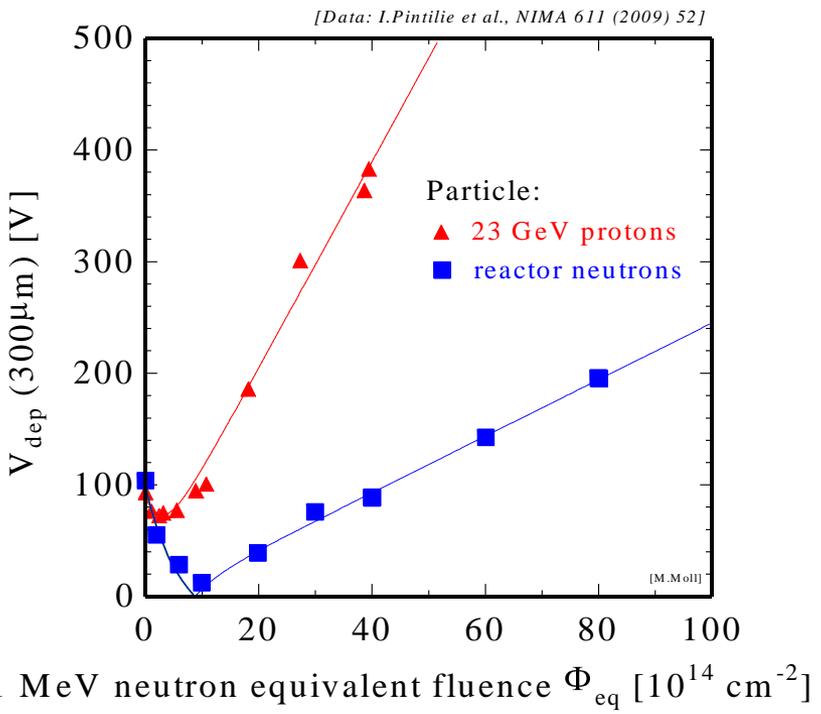
*(for experts: there is no “real” type inversion, a more clear understanding of the observed effects is obtained by investigating directly the internal electric field; look for: TCT, MCZ, double junction)*



### • Common to all materials (after hadron irradiation, not after $\gamma$ irradiation):

- reverse current increase
- increase of trapping (electrons and holes) within  $\sim 20\%$

- **Epitaxial silicon** (*EPI-DO*, 72  $\mu\text{m}$ , 170  $\Omega\text{cm}$ , diodes)  
irradiated with **23 GeV protons** or **reactor neutrons**

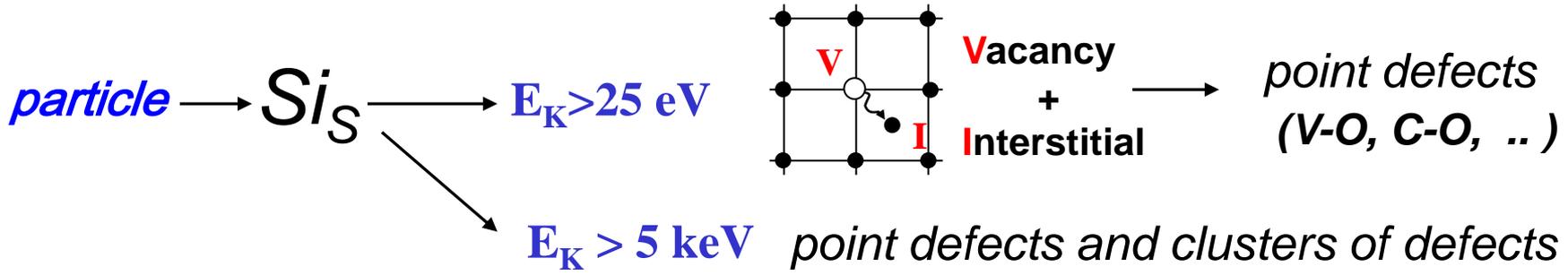


depletion voltage  $\rightarrow$

$$V_{\text{dep}} = \frac{q_0}{\epsilon\epsilon_0} \cdot |N_{\text{eff}}| \cdot d^2$$

$\leftarrow$  absolute effective space charge density

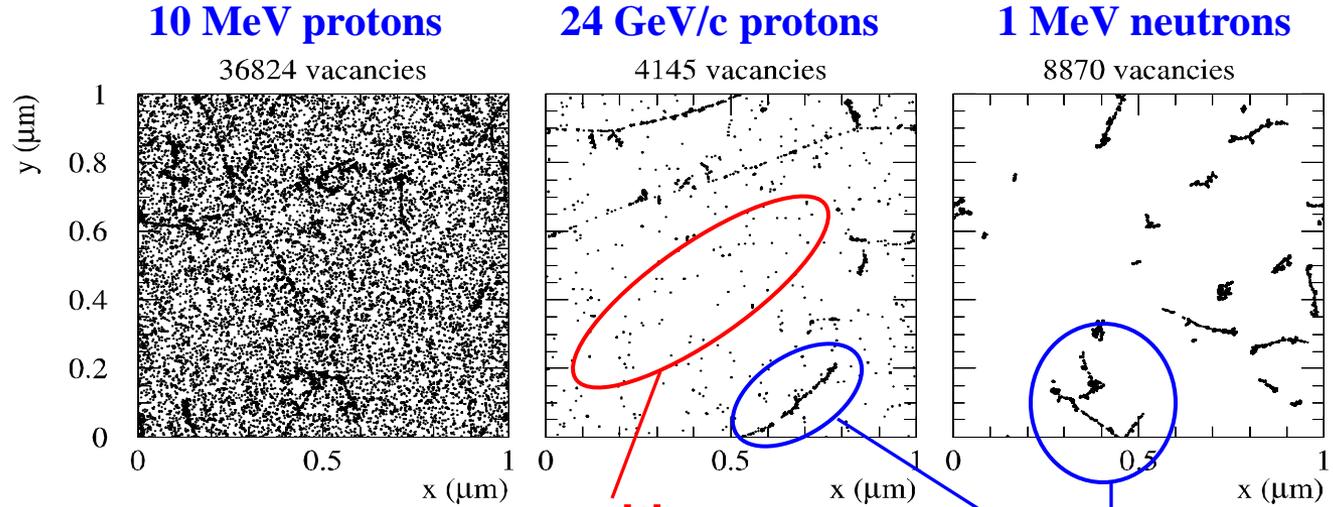
# Why is proton and neutron damage different?



### Simulation:

Initial distribution of vacancies in  $(1\mu\text{m})^3$  after  $10^{14}$  particles/cm<sup>2</sup>

[Mika Huhtinen NIMA 491(2002) 194]



- A 'simplified' explanation for the 'compensation effects'**
  - Defect clusters produce predominantly **negative space charge**
  - Point defects produce predominantly **positive space charge** (in 'oxygen rich' silicon)

For the experts: Note the NIEL violation

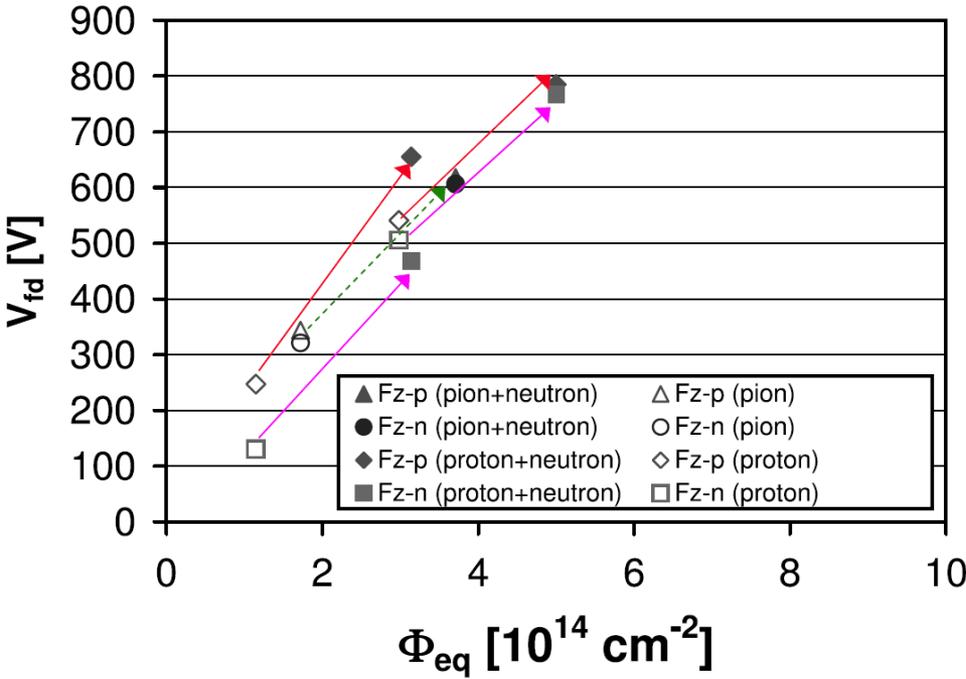


# Mixed irradiations – Change of $N_{eff}$

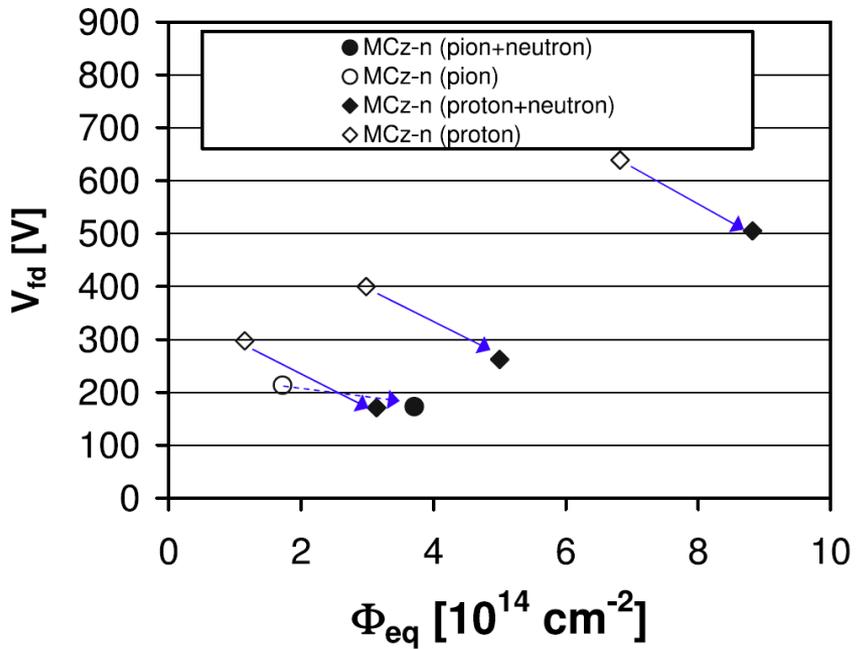


- Exposure of FZ & MCZ silicon sensors to ‘mixed’ irradiations
  - First step: Irradiation with protons or pions
  - Second step: Irradiation with neutrons

### FZ: Accumulation of damage



### MCZ: Compensation of damage



[G.Kramberger et al., ‘Performance of silicon pad detectors after mixed irradiations with neutrons and fast charged hadrons’, NIMA 609 (2009) 142-148]

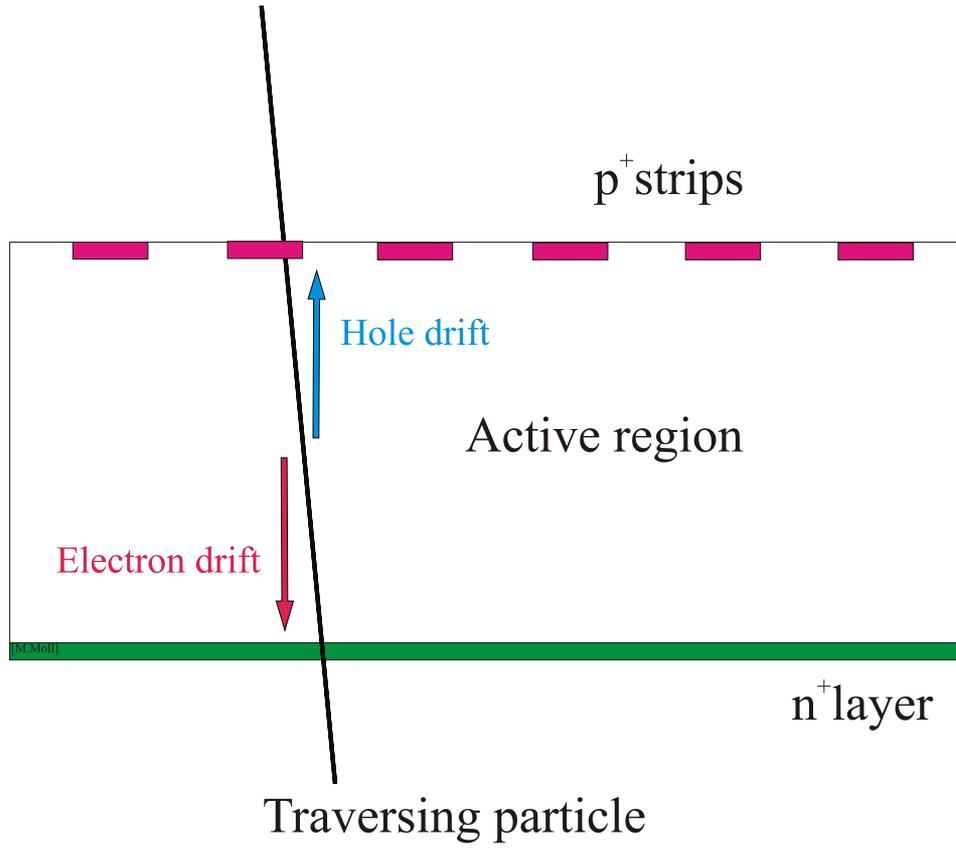


# Advantage of non-inverting material

p-in-n detectors (schematic figures!)



Fully depleted detector  
(non – irradiated):





# Advantage of non-inverting material



## p-in-n detectors (schematic figures!)

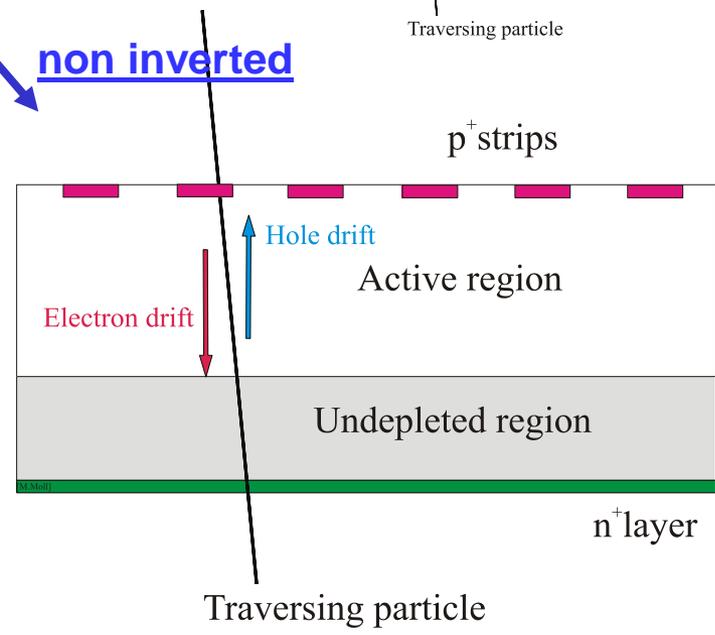
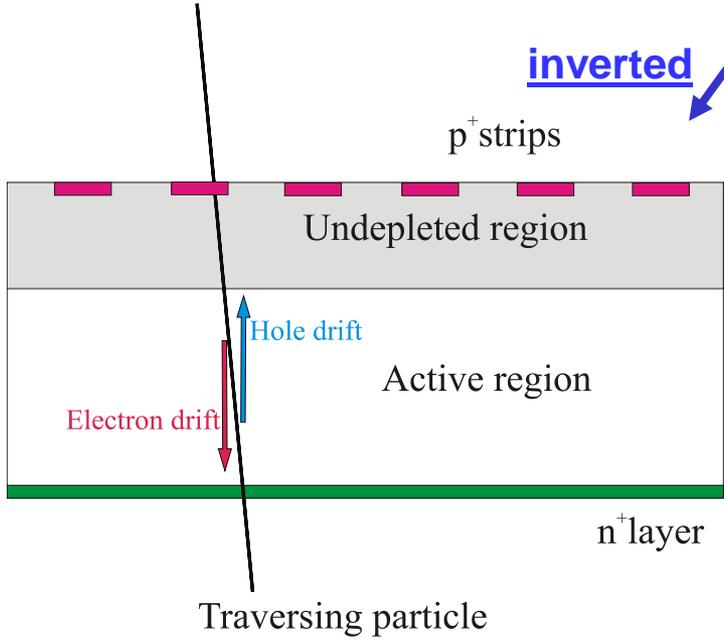
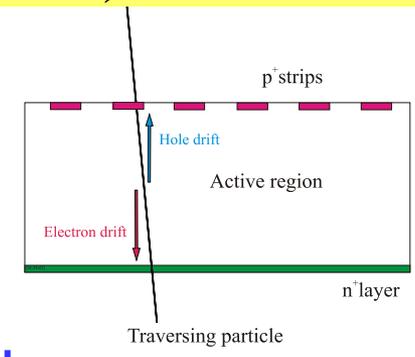
*Be careful, this is a very schematic explanation, reality is more complex !*

### Fully depleted detector (non – irradiated):

heavy irradiation

inverted

non inverted



inverted to “p-type”, under-depleted:

- Charge spread – degraded resolution
- Charge loss – reduced CCE

non-inverted, under-depleted:

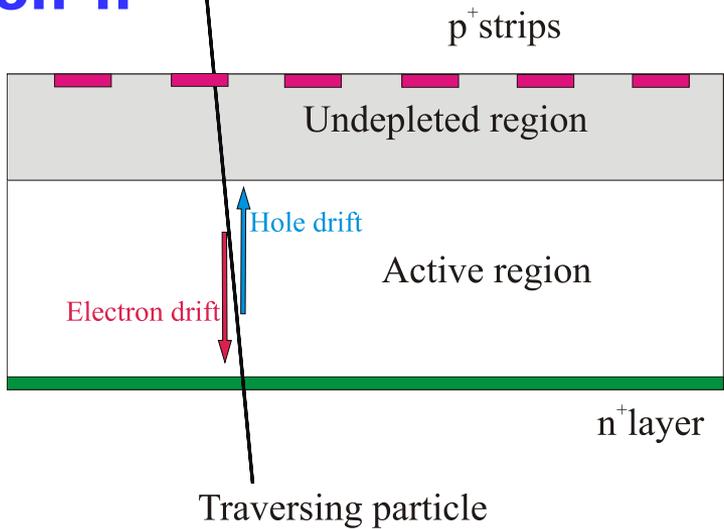
- Limited loss in CCE
- Less degradation with under-depletion

## p-in-n versus n-in-p (or n-in-n) detectors

**n-type silicon after high fluences:**

(type inverted)

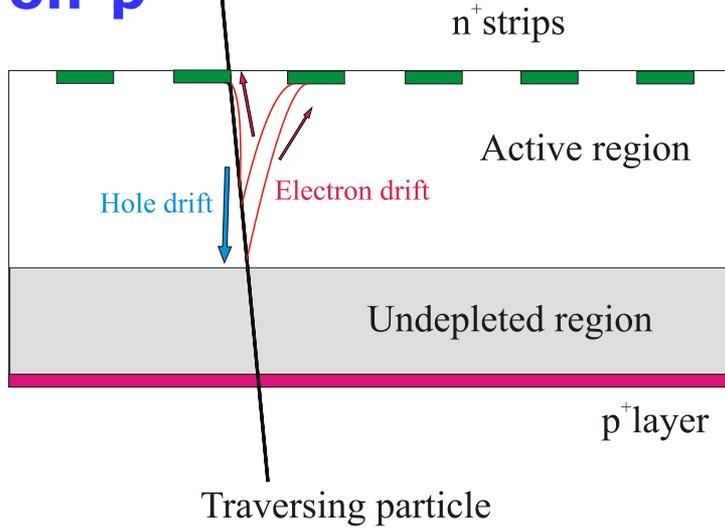
**p<sup>+</sup>on-n**



**p-type silicon after high fluences:**

(still p-type)

**n<sup>+</sup>on-p**



**p-on-n silicon, under-depleted:**

- Charge spread – degraded resolution
- Charge loss – reduced CCE

**n-on-p silicon, under-depleted:**

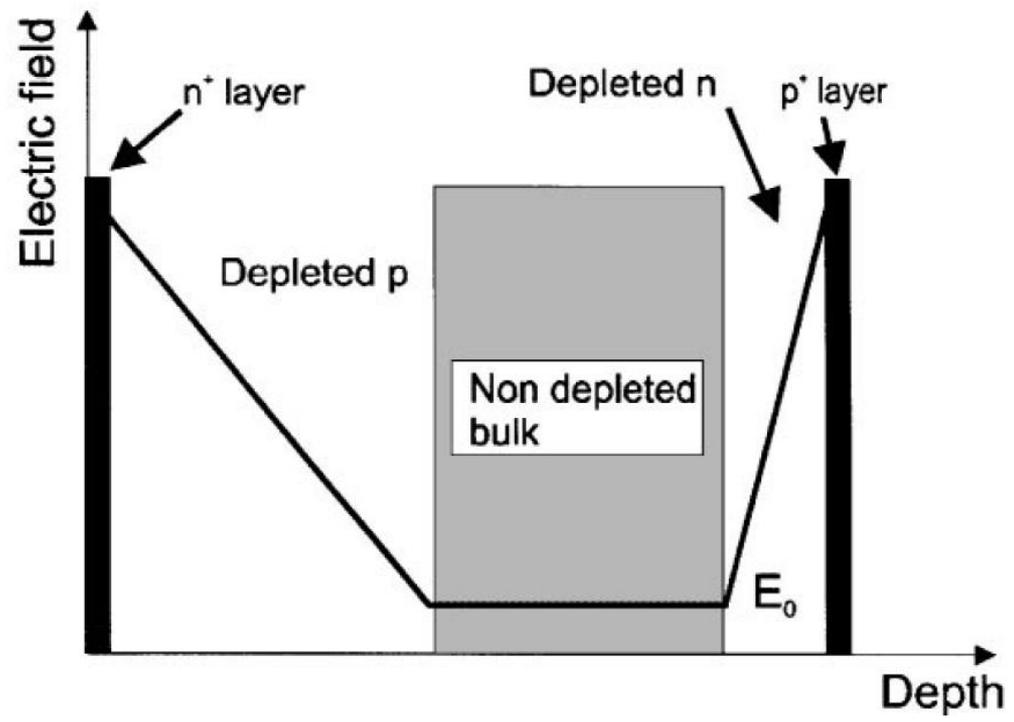
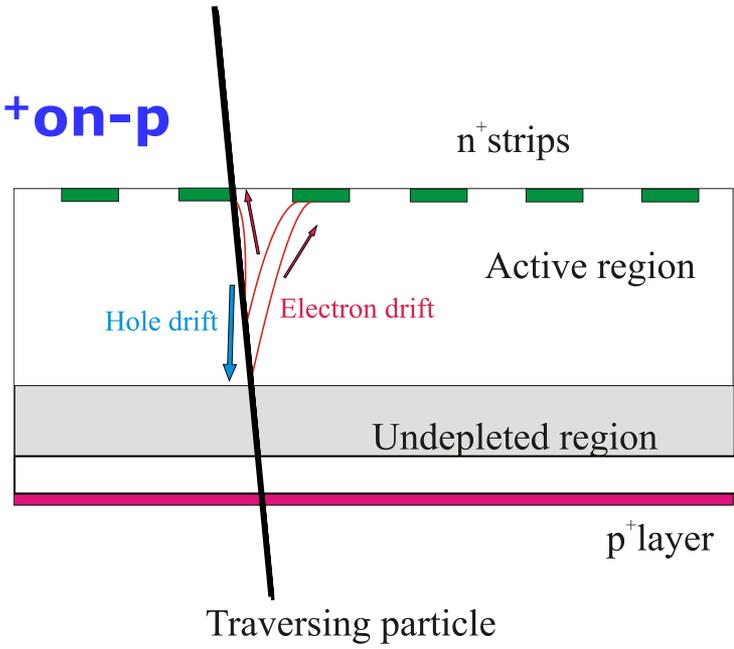
- Limited loss in CCE
- Less degradation with under-depletion
- Collect electrons (3 x faster than holes)

*Comments:*

*- Instead of n-on-p also n-on-n devices could be used*

**p-type silicon after high fluences:**  
(still “p-type”)

**n<sup>+</sup>on-p**



- **Dominant junction close to n+ readout strip for FZ n-in-p**
- **For MCZ p-in-n even more complex fields have been reported:**
  - no “type inversion”(SCSI) = dominant field remains at p implant
  - “equal double junctions” with almost symmetrical fields on both sides

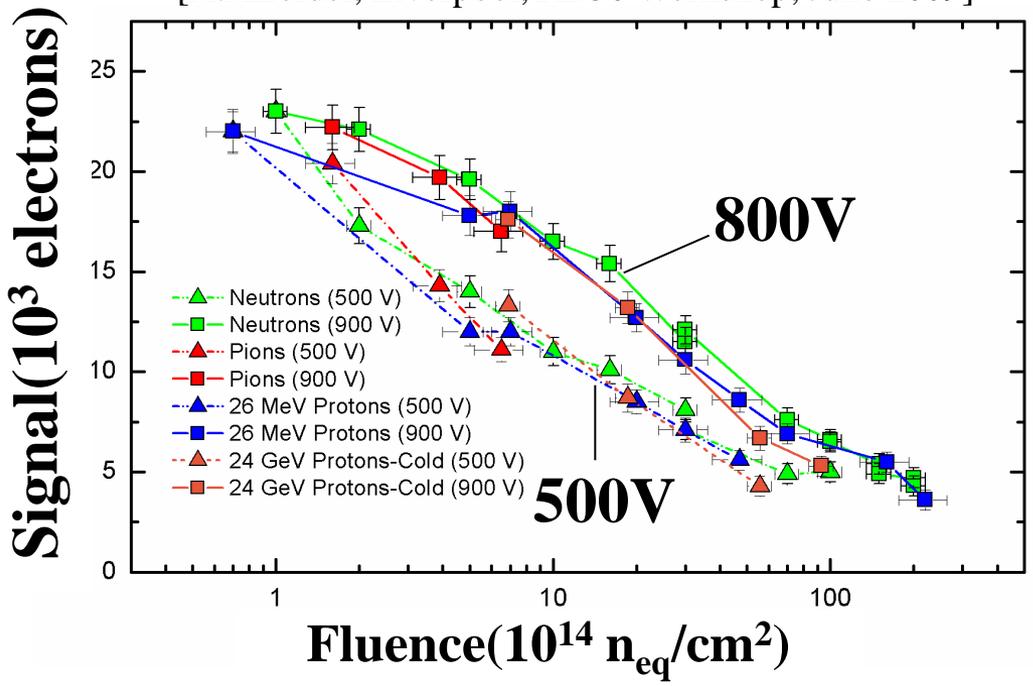


# FZ n-in-p microstrip detectors (n, p, p - irradi)



- **n-in-p microstrip p-type FZ detectors** (Micron, 280 or 300μm thick, 80μm pitch, 18μm implant )
- **Detectors read-out with 40MHz** (SCT 128A)

[A.Affolder, Liverpool, RD50 Workshop, June 2009]



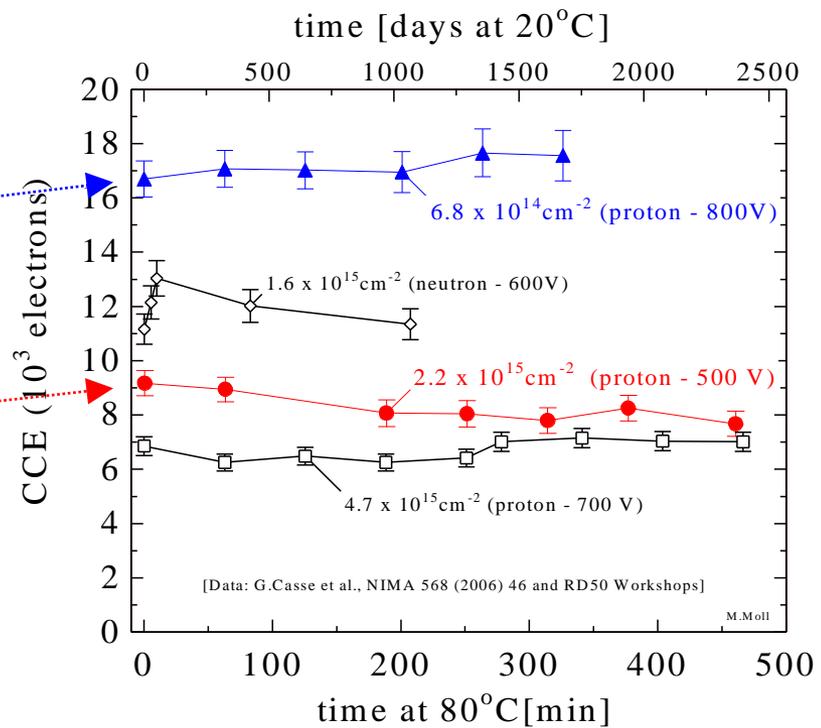
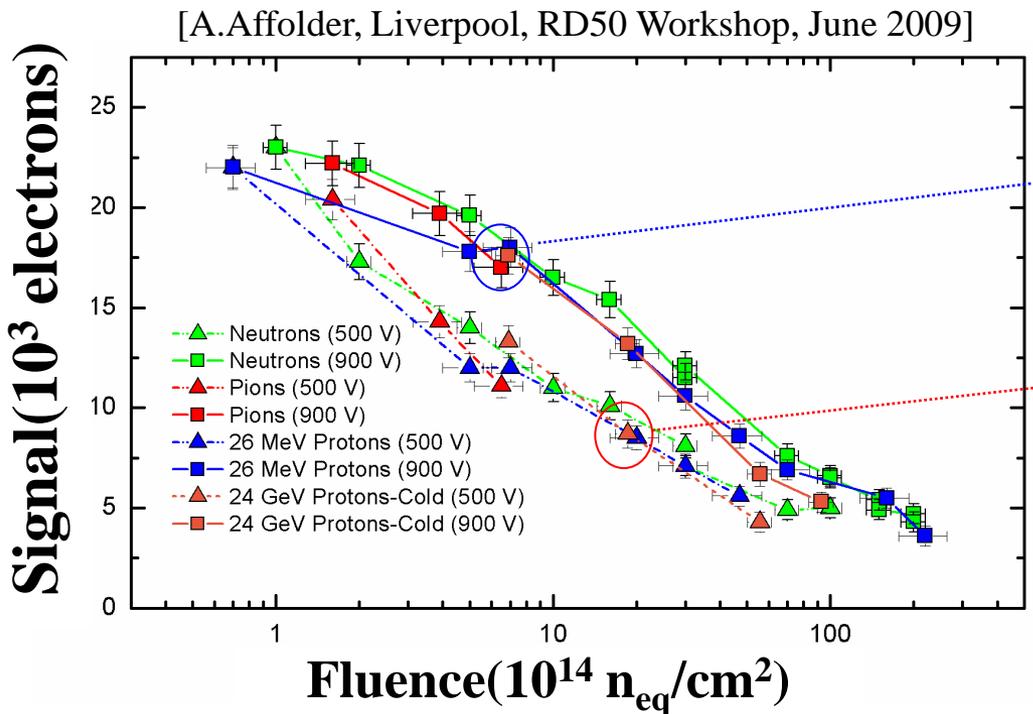
- **CCE: ~7300e (~30%)**  
after ~ 1×10<sup>16</sup>cm<sup>-2</sup> 800V
- **n-in-p sensors are strongly considered for ATLAS upgrade** (previously p-in-n used)



# FZ n-in-p microstrip detectors (n, p, $\pi$ – irradiad)



- **n-in-p microstrip p-type FZ detectors** (Micron, 280 or 300 $\mu$ m thick, 80 $\mu$ m pitch, 18 $\mu$ m implant )
- **Detectors read-out with 40MHz** (SCT 128A)



- **CCE: ~7300e (~30%)**  
after  $\sim 1 \times 10^{16} cm^{-2}$  800V
- **n-in-p sensors are strongly considered for ATLAS upgrade** (previously p-in-n used)

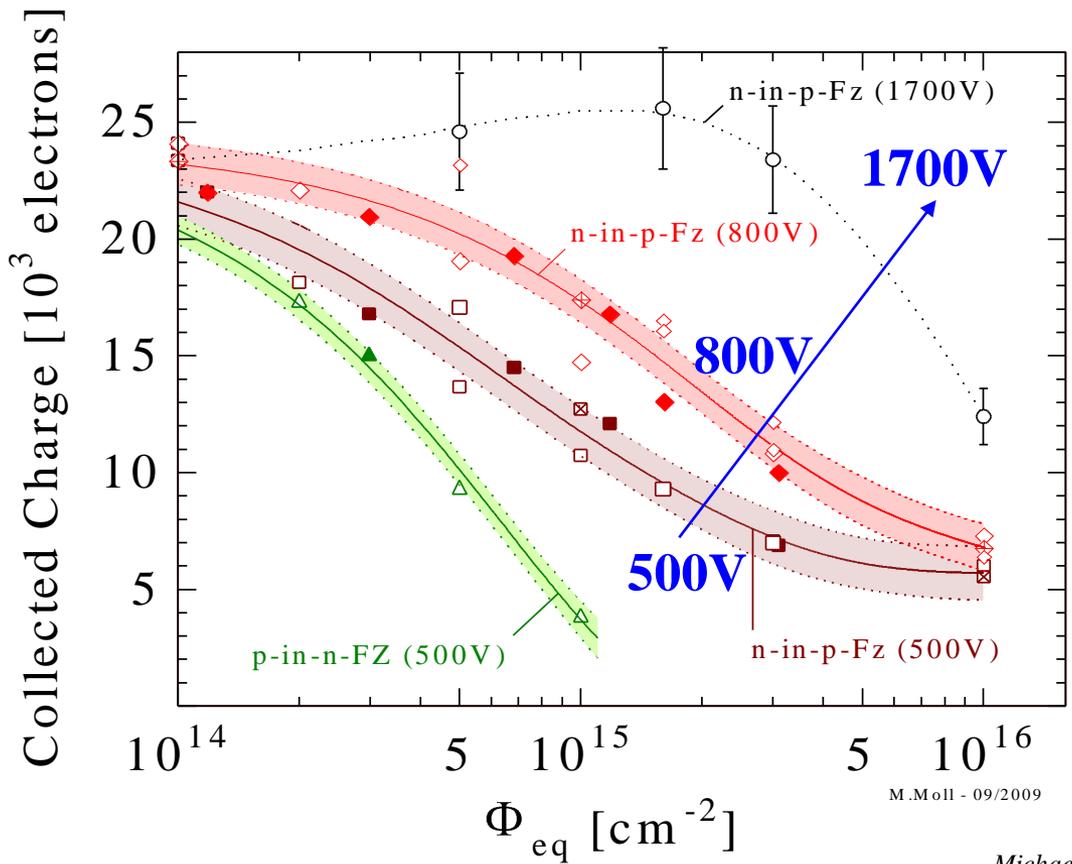
- **no reverse annealing in CCE measurements for neutron and proton irradiated detectors**



# Good performance of planar sensors at high fluence



- Why do planar silicon sensors with n-strip readout give such high signals after high levels ( $>10^{15}$  cm<sup>-2</sup> p/cm<sup>2</sup>) of irradiation?
  - Extrapolation of charge trapping parameters obtained at lower fluences would predict much lower signal!
  - Assumption: ‘Charge multiplication effects’ as even CCE > 1 was observed



FZ Silicon Strip Sensors

- n-in-p (FZ), 300μm, 500V, 23GeV p [1]
- n-in-p (FZ), 300μm, 500V, neutrons [1,2]
- ⊗ n-in-p (FZ), 300μm, 500V, 26MeV p [1]
- ◆ n-in-p (FZ), 300μm, 800V, 23GeV p [1]
- ◇ n-in-p (FZ), 300μm, 800V, neutrons [1,2]
- ◊ n-in-p (FZ), 300μm, 800V, 26MeV p [1]
- n-in-p (FZ), 300μm, 1700V, neutrons [2]
- ▲ p-in-n (FZ), 300μm, 500V, 23GeV p [1]
- △ p-in-n (FZ), 300μm, 500V, neutrons [1]

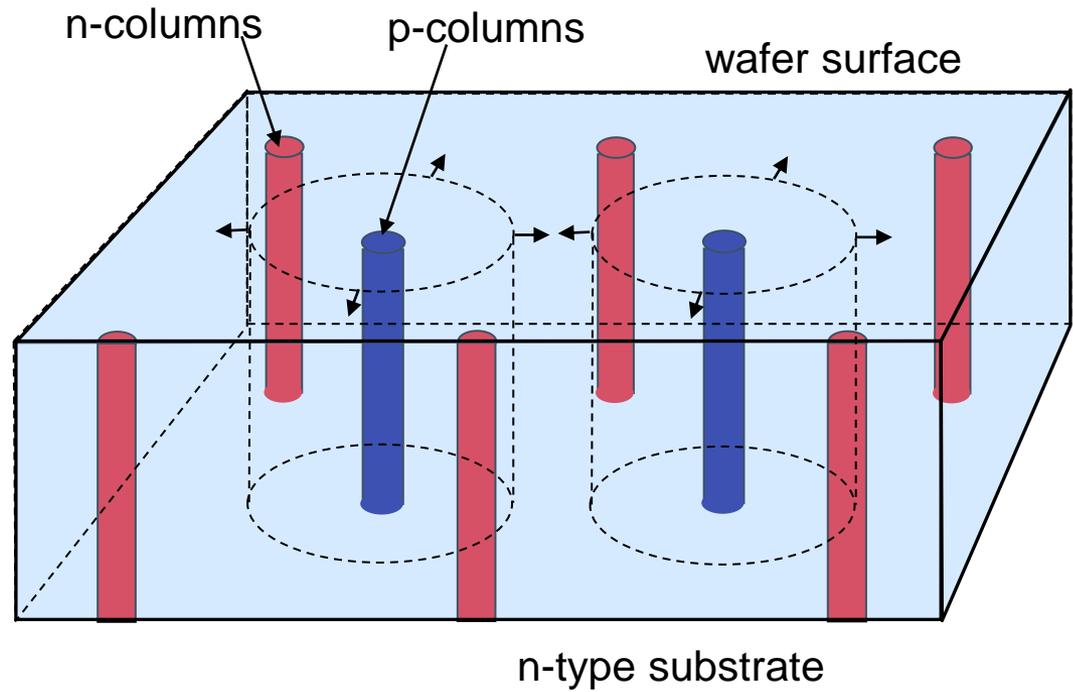
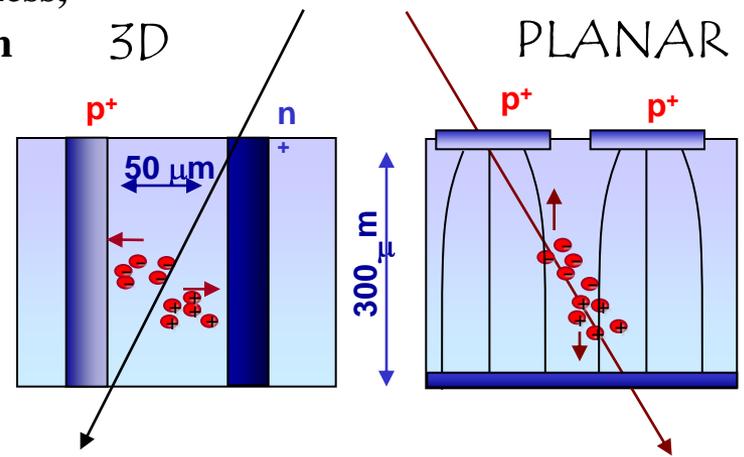
References:

- [1] G.Casse, VERTEX 2008 (p/n-FZ, 300μm, (-30°C, 25ns)
- [2] I.Mandic et al., NIMA 603 (2009) 263 (p-FZ, 300μm, -20°C to -40°C, 25ns)

- Which voltage can be applied?

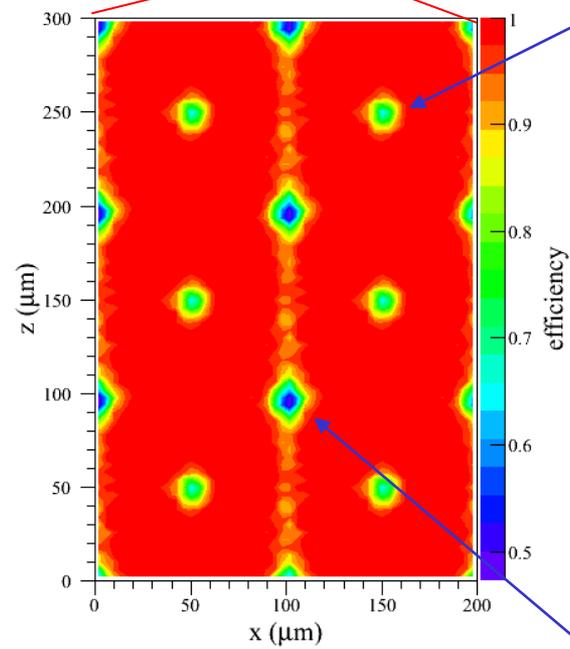
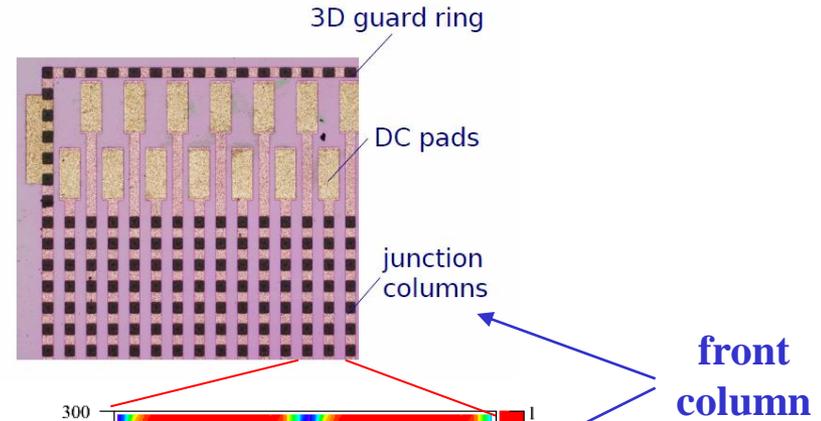
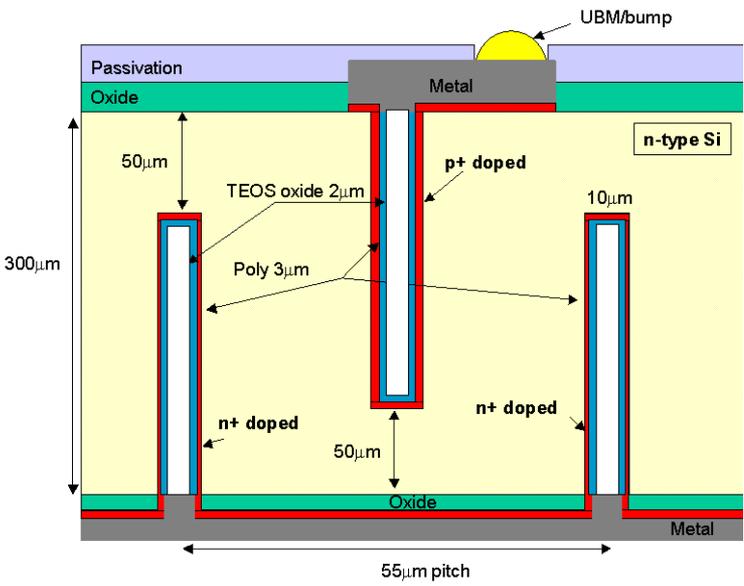
# 3D detector - concept

- **“3D” electrodes:**
  - narrow columns along detector thickness,
  - diameter:  $10\mu\text{m}$ , distance:  $50 - 100\mu\text{m}$
- **Lateral depletion:**
  - lower depletion voltage needed
  - thicker detectors possible
  - fast signal
  - radiation hard



- DDTC – Double sided double type column

[G.Fleta, RD50 Workshop, June 2007]



- Testbeam data – Example: efficiency map [M.Koehler, Freiburg Uni, RD50 Workshop June 09]

- Processing of 3D sensors is challenging, but many good devices with reasonable production yield produced.

see lecture by *Manuel Lozano*

- Competing e.g. for ATLAS IBL pixel sensors

**40V applied**  
**~98% efficiency**

Property	Diamond	GaN	4H SiC	Si
$E_g$ [eV]	5.5	3.39	3.3	1.12
$E_{breakdown}$ [V/cm]	$10^7$	$4 \cdot 10^6$	$2.2 \cdot 10^6$	$3 \cdot 10^5$
$\mu_e$ [ $cm^2/Vs$ ]	1800	1000	800	1450
$\mu_h$ [ $cm^2/Vs$ ]	1200	30	115	450
$v_{sat}$ [cm/s]	$2.2 \cdot 10^7$	-	$2 \cdot 10^7$	$0.8 \cdot 10^7$
e-h energy [eV]	13	8.9	7.6-8.4	3.6
e-h pairs/ $X_0$	4.4	~2-3	4.5	10.1

- **Diamond: wider bandgap**  
 $\Rightarrow$  lower leakage current  
 $\Rightarrow$  less cooling needed  
 $\Rightarrow$  less noise

- **Signal produced by m.i.p:**  
**Diamond** 36 e/ $\mu m$   
**Si** 89 e/ $\mu m$   
 $\Rightarrow$  Si gives more charge than diamond

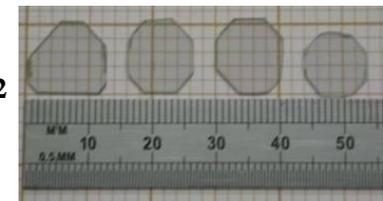
- **GaAs, SiC and GaN**  $\Rightarrow$  strong radiation damage observed  
 $\Rightarrow$  no potential material for LHC upgrade detectors  
*(judging on the investigated material)*

- **Diamond (RD42)**  $\Rightarrow$  good radiation tolerance *(see later)*  
 $\Rightarrow$  already used in LHC beam condition monitoring systems  
 $\Rightarrow$  considered as potential detector material for sLHC pixel sensors

poly-CVD Diamond  
 -16 chip ATLAS  
 pixel module



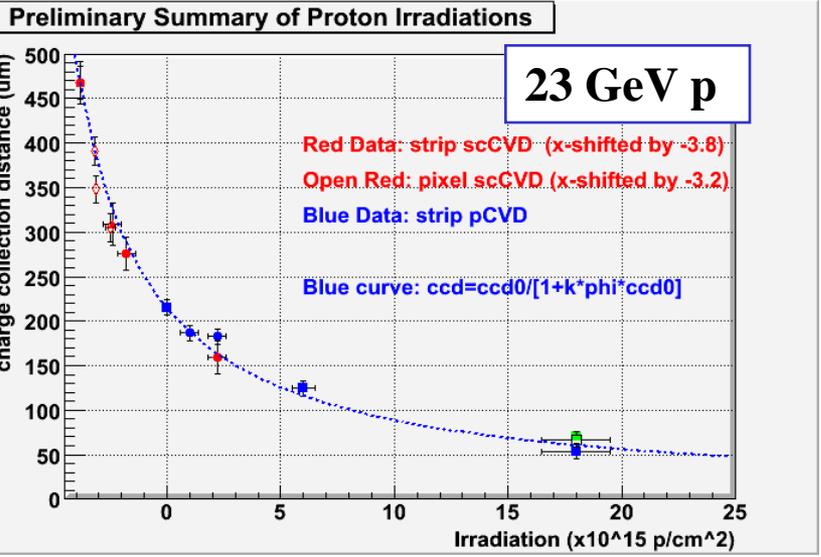
single crystal CVD  
 Diamond of few  $cm^2$



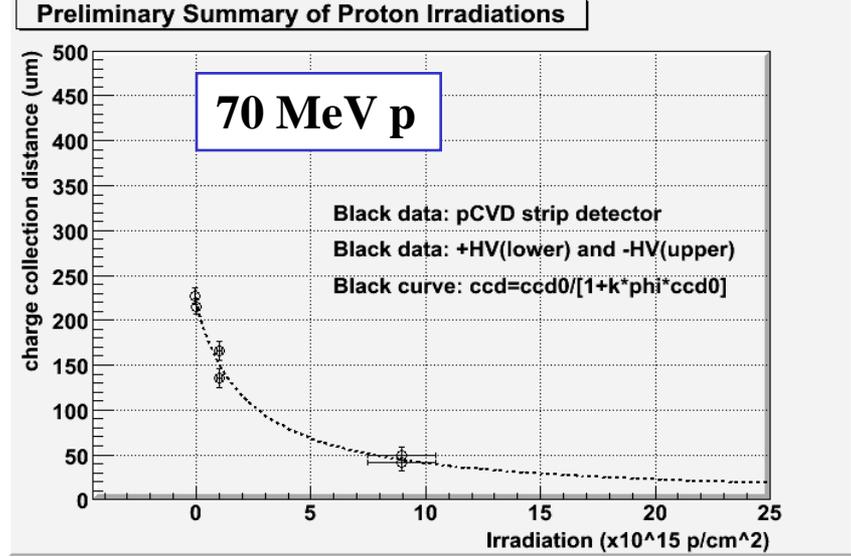
**Diamond sensors are heavily used in  
 LHC Experiments for Beam Monitoring**



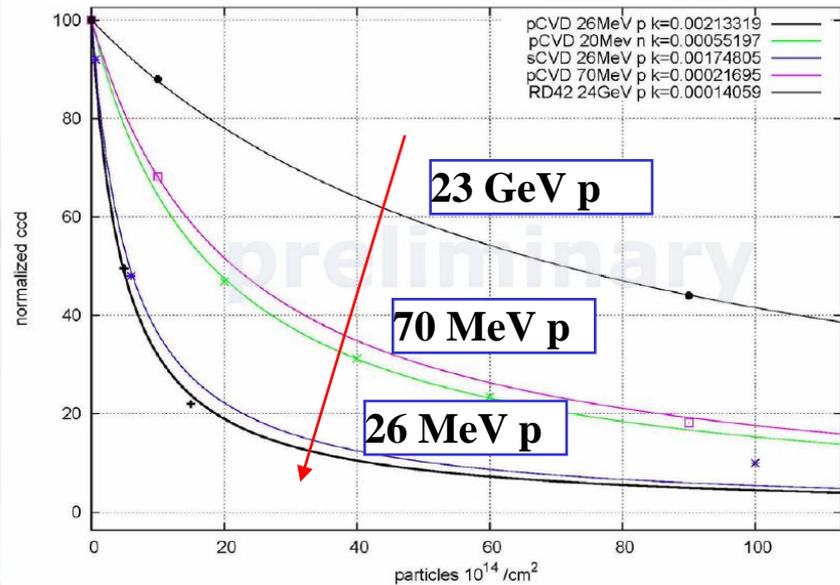
# Are diamond sensors radiation hard?



[RD42, LHCC Status Report, Feb. 2010]



[RD42, LHCC Status Report, Feb. 2010]



[V.Rylov, CERN ESE Seminar 9.11.2009]

- Most published results on 23 GeV protons
- 70 MeV protons 3 times more damaging than 23 GeV protons
- 25 MeV protons seem to be even more damaging (Preliminary: RD42 about to cross check the data shown to the left)
- In line with NIEL calc. for Diamond [W. de Boer et al. Phys.Status Solidi 204:3009,2007]



# Summary – Radiation Damage



## • Radiation Damage in Silicon Detectors

- Change of **Depletion Voltage** (internal electric field modifications, “type inversion”, reverse annealing, loss of active volume, ...) (can be influenced by defect engineering!)
- Increase of **Leakage Current** (same for all silicon materials)
- Increase of **Charge Trapping** (same for all silicon materials)

**Signal to Noise ratio** is quantity to watch (material + geometry + electronics)

## • Microscopic defects & Damage scaling factors

- Microscopic crystal defects are the origin to detector degradation.
- **NIEL** – Hypothesis used to scale damage of different particles with different energy
- Different particles produce different types of defects! (NIEL – violation!)
- There has been an enormous progress in the last 5 years in understanding defects.

**Details in next lecture by  
*Ioana Pintilie* on defects.**

## • Approaches to obtain radiation tolerant devices:

- **Material Engineering:**
  - explore and develop new silicon materials (oxygenated Si)
  - use of other semiconductors (Diamond)
- **Device Engineering:**
  - look for other sensor geometries
  - 3D, thin sensors, n-in-p, n-in-n, ...



# Detectors for the LHC upgrade



- **At fluences up to  $10^{15} \text{cm}^{-2}$  (outer layers – ministrip sensors):**

The change of the depletion voltage and the large area to be covered by detectors are major problems.

- **n-MCZ silicon detectors** show good performance in mixed fields due to compensation of charged hadron damage and neutron damage ( $N_{\text{eff}}$  compensation) (more work needed)
- **p-type silicon microstrip detectors show very encouraging results**  
 $\text{CCE} \approx 6500 \text{ e}; \Phi_{\text{eq}} = 4 \times 10^{15} \text{ cm}^{-2}, 300 \mu\text{m}$ , immunity against reverse annealing!

This is presently the “most considered option” for the ATLAS SCT upgrade

- **At fluences  $> 10^{15} \text{cm}^{-2}$  (Innermost tracking layers – pixel sensors)**

The active thickness of any silicon material is significantly reduced due to trapping.

Collection of electrons at electrodes essential: Use n-in-p or n-in-n detectors!

- **Recent results show that planar silicon sensors might still give sufficient signal**, (still some interest in epitaxial silicon and thin sensor options)
- **3D detectors** : looks promising, drawback: technology has to be optimized!  
Many collaborations and sensor producers working on this.
- **Diamond** has become an interesting option (*Higher damage due to low energy protons?*)

- **Questions to be answered:**

- **a) Can we profit from avalanche effects and control them?**      ? ? ?
- **b) Can we profit from compensation effects in mixed fields?**
- **c) Can we understand detector performance on the basis of simulations using defect parameters as input?**

Details in lecture by Phil Allport



# Acknowledgements & References



- **Many thanks to the MC-PAD Network for the invitation to give this lecture**
- **Most references to particular works given on the slides**
- **Some additional material taken from the following presentations:**
  - *RD50 presentations: <http://www.cern.ch/rd50/>*
  - *Anthony Affolder: Presentations on the RD50 Workshop in June 2009 (sATLAS fluence levels)*
  - *Frank Hartmann: Presentation at the VCI conference in February 2010 (Diamond results)*
- **Books containing chapters about radiation damage in silicon sensors**
  - *Helmuth Spieler, “Semiconductor Detector Systems”, Oxford University Press 2005*
  - *Frank Hartmann, “Evolution of silicon sensor technology in particle physics”, Springer 2009*
  - *L.Rossi, P.Fischer, T.Rohe, N.Wermes “Pixel Detectors”, Springer, 2006*
  - *Gerhard Lutz, “Semiconductor radiation detectors”, Springer 1999*
- **Research collaborations and web sites**
  - *The RD50 collaboration (<http://www.cern.ch/rd50>) - Radiation Tolerant Silicon Sensors*
  - *The RD39 collaboration – Cryogenic operation of Silicon Sensors*
  - *The RD42 collaboration – Diamond detectors*
  - *ATLAS IBL, ATLAS and CMS upgrade groups*